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22 March 2002

SUBJECT: Authorization for Release of Technical Information, Control Number: **AFRL-PR-ED-VG-2002-065**
Capt. Rene I. Gonzalez, "Synthesis and In-Situ Atomic Oxygen Erosion Studies of Space-Survivable
Hybrid Organic/Inorganic Polyhedral Oligomeric Silsesquioxane Polymers"

Ph.D. Dissertation Defense

(Statement A)

(University of Florida, FL, 04 April 2002) (Deadline: 04 Apr 02)



Chemical Engineering Department

**Synthesis and In-Situ Atomic Oxygen Erosion
Studies of Space-Survivable Hybrid
Organic/Inorganic Polyhedral Oligomeric
Silsesquioxane Polymers**

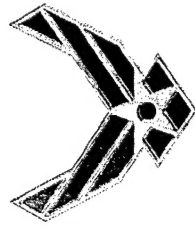
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**Ph.D. Dissertation Defense
for**

Capt Rene I. Gonzalez

**Materials Application Branch
Space and Missile Propulsion Division
Air Force Research Laboratory**

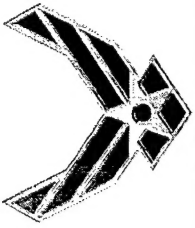
Research Advisor: Prof. Gar B. Hoflund



Polymeric Materials



- Cost is the variable plaguing all space missions. (\$6,000 to \$10,000/lb to put payload in orbit)
- Materials are one of the main drivers of cost for space missions.
- Polymers offer many advantages (lightweight, easy to process, versatility)
- However, polymers are subject to severe degradation in Low Earth Orbit space environment

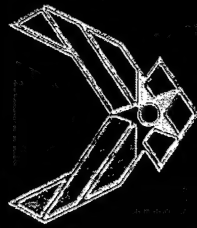


LEO Environment

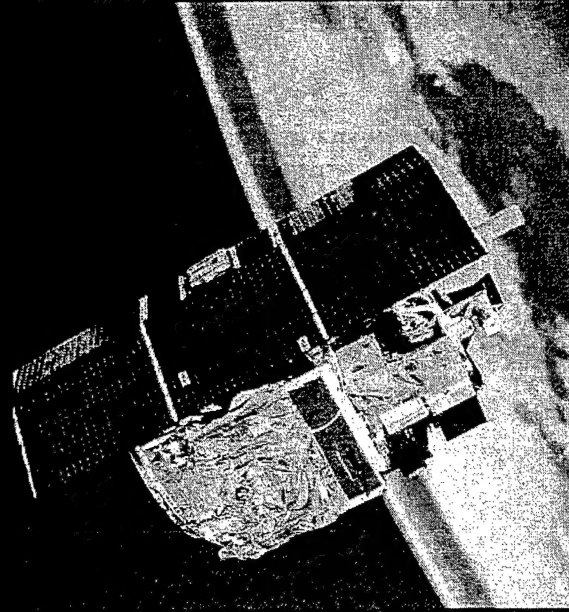
(Altitudes of 200 to 1500 km)



- Atomic Oxygen
 - $\sim 10^8$ atoms/cm³
 - Formed from photo-dissociation of O₂ in atmosphere.
 - Actual flux on spacecraft traveling at 8 to 12 km/s $\sim 10^{15}$ atoms/cm²•s
 - collision energy ~ 5 eV
- Low-energy and high energy charged particles.
- Thermal cycling -50 to 150°C
- Solar UV and VUV radiation
 - VUV wavelengths in LEO extend below 290nm.
 - Bond scission and radical formation can lead to embrittlement.



Goal: Develop Multi-Functional, Space-Survivable Materials (AFOSR/ER)



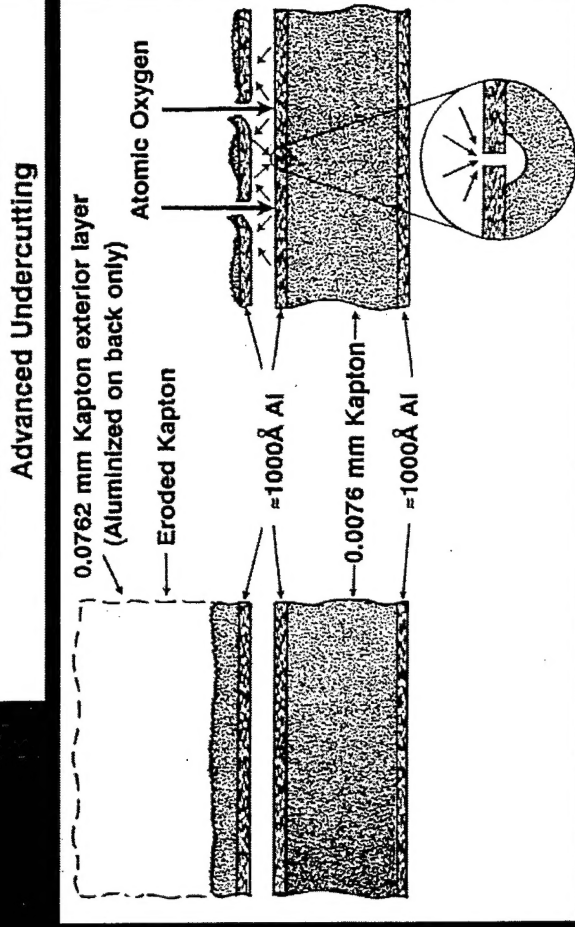
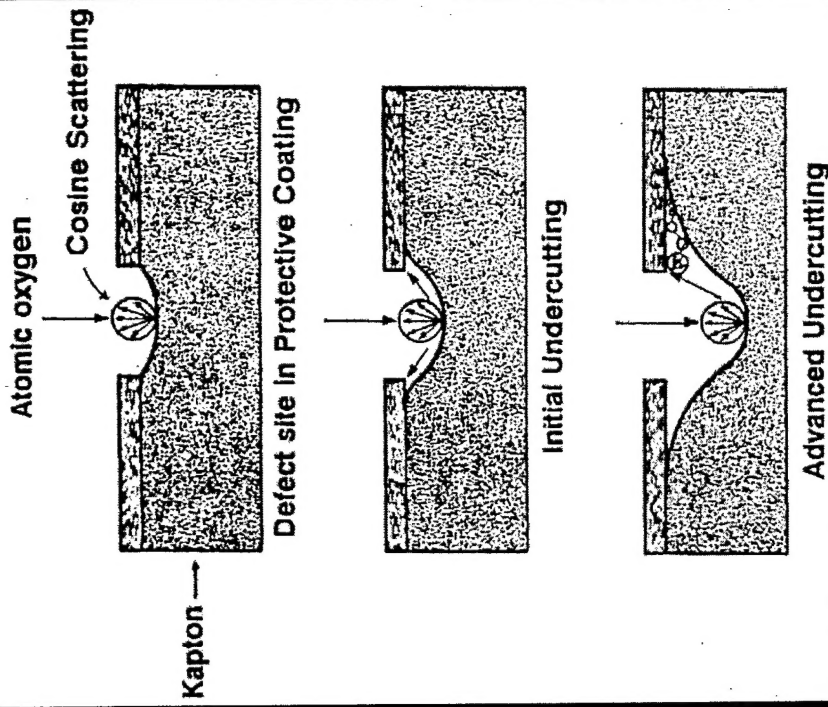
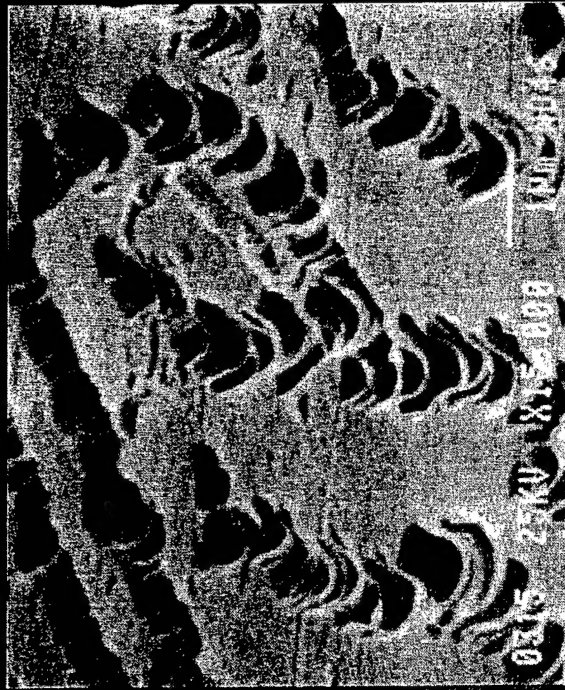
Satellites & Space Systems

Objectives

- Increase Space Resistance (AO, particle & VUV radiation, thermal cycling) of Polymeric Materials
- Self-Passivating/Self-Rigidizing/Self-Healing based on Hybrid organic/ inorganic nanocomposite incorporation

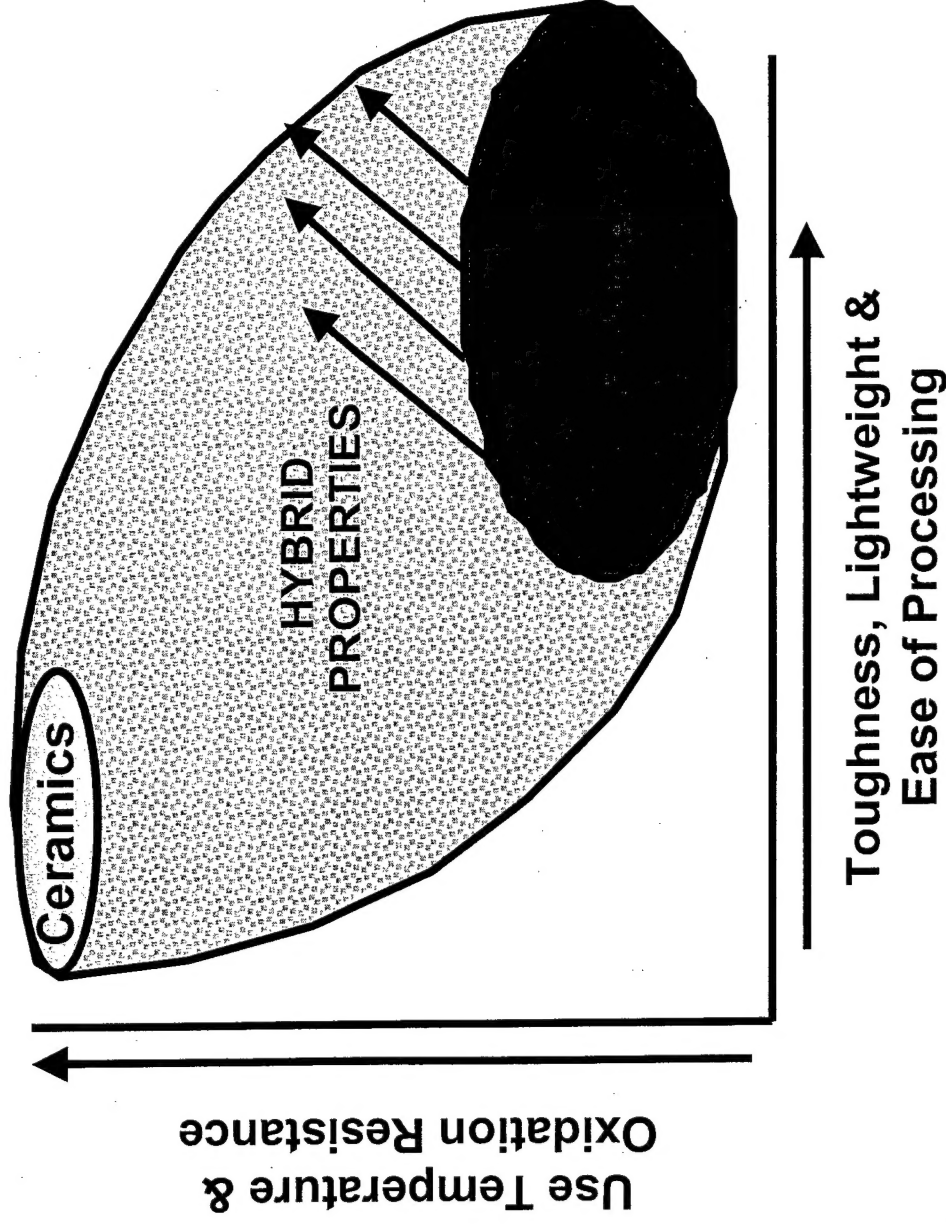
Atomic Oxygen Reaction Efficiency cm ³ /atom		
Material	Rel. Rates*	LEO
Kapton	1	3.0 x 10 ⁻²⁴
Polyethylene	0.9	3.7 x 10 ⁻²⁴
FEP Teflon	<0.03	<0.05 x 10 ⁻²⁴
FEP Teflon (Solar Max)	0.6	1.0 x 10 ⁻²⁴
Siloxane-imide block copolymers(25% /75%)	0.1	0.3 x 10 ⁻²⁴
Epoxy	0.6	1.7 x 10 ⁻²⁴

AO undercutting of LDEF Aluminized-Kapton Multilayer Insulation



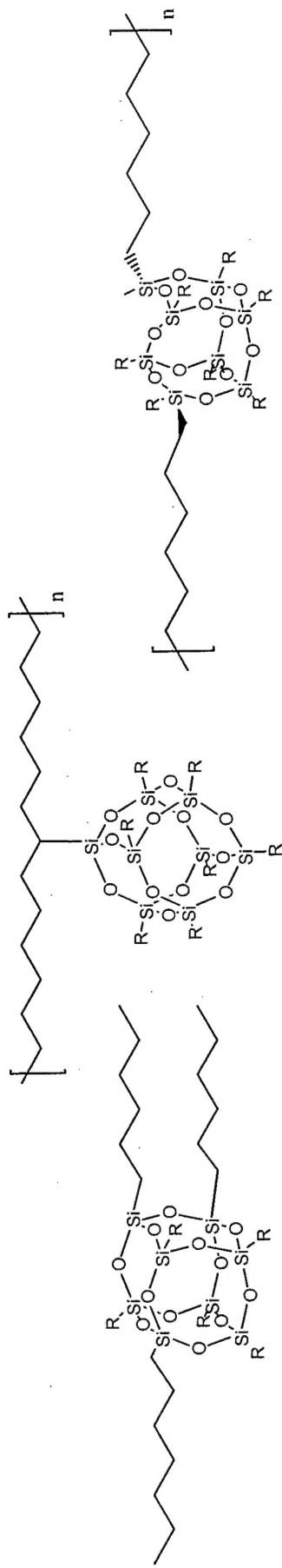
Propulsion & Space Technology is Limited by Material Properties

Goal: Develop High Performance Polymers that REDEFINE material properties



•Hybrid plastics can bridge the barrier between ceramics and polymers

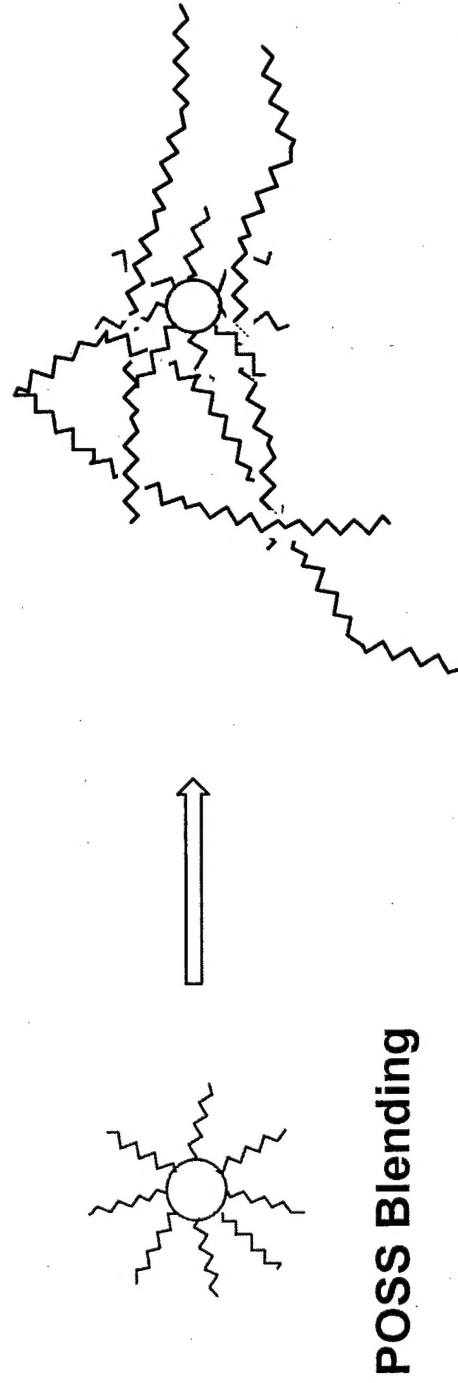
POSS Polymer Incorporation



Cross-linker

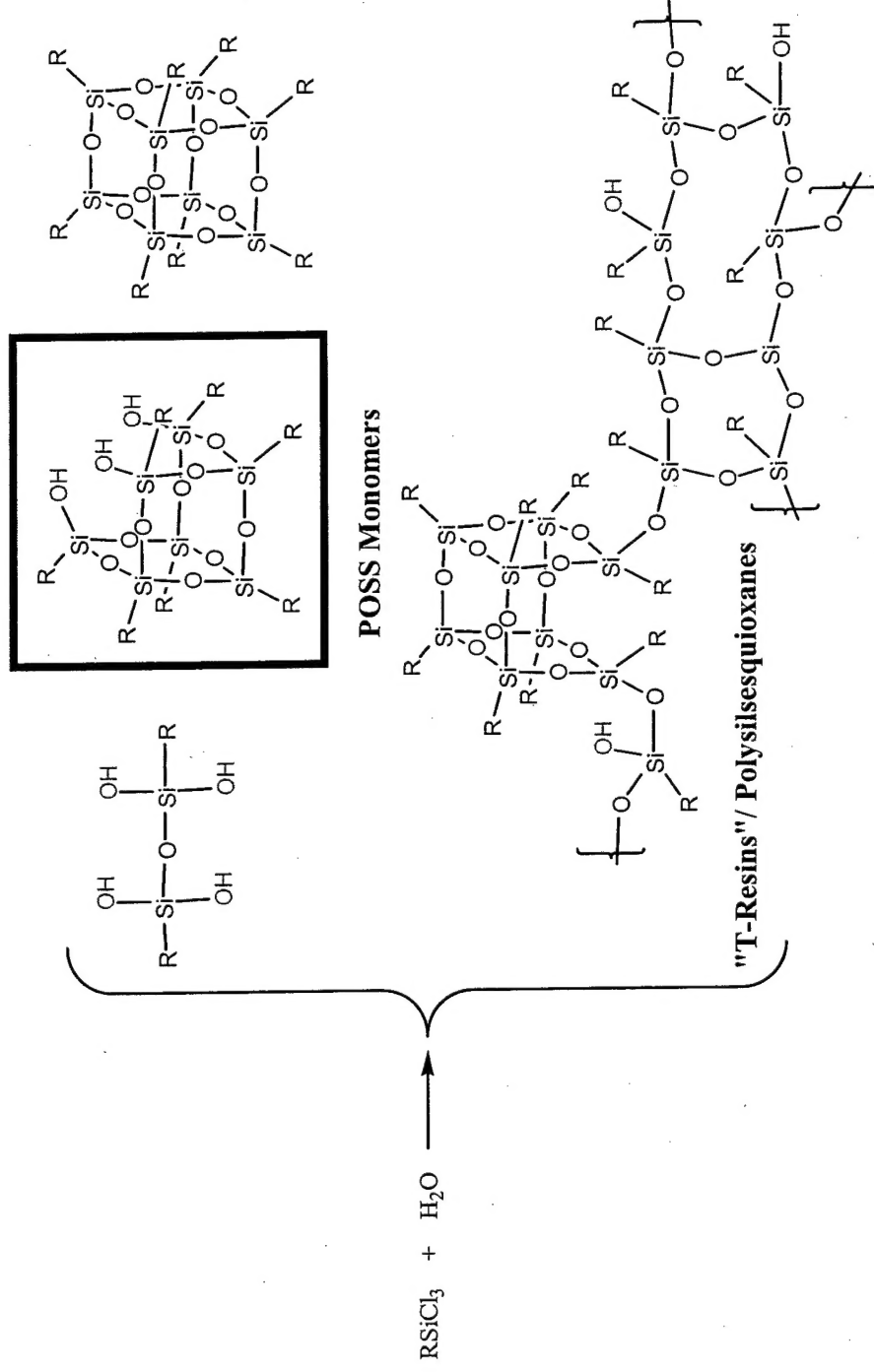
Pendant Polymer

Bead Copolymer



POSS Blending

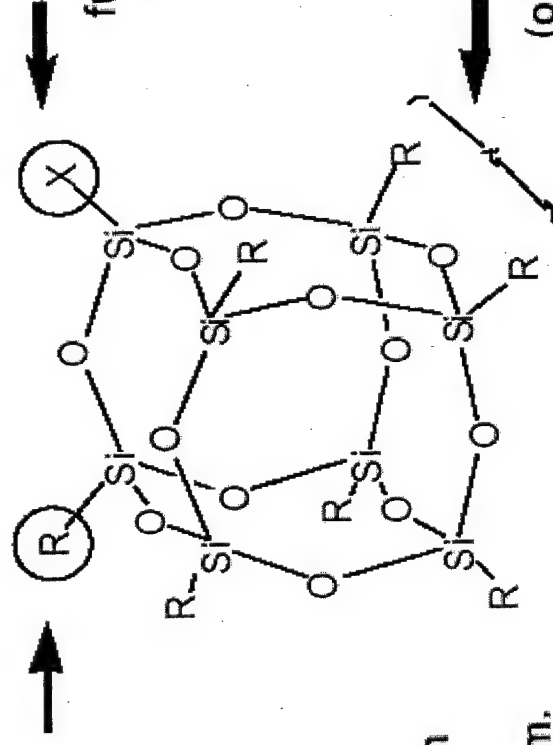
POSS = Polyhedral Oligomeric Silsesquioxane



- Traditional silsesquioxane chemistry focused on "T-Resins"
- The maximization of property enhancements in polymers results from interaction at the nano-level

Anatomy of a POSS Nanostructure

Nonreactive organic (R) groups for solubilization and compatibilization.



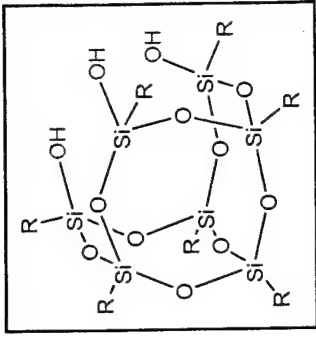
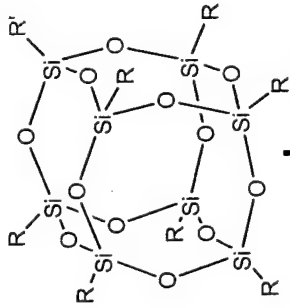
Nanoscopic in size with an Si-Si distance of 0.5 nm and a R-R distance of 1.5 nm.

Thermally and chemically robust hybrid (organic-inorganic) framework.

Precise three-dimensional structure for molecular level reinforcement of polymer segments and coils.

POSS Monomer/Polymer Trees

Hybrid
Plastics™



halides

alcohols

esters

acids

bisphenols

acid chlorides

aryldiacids

nitriles

amines

isocyanates

arylbisamines

aryldiisocyanates

silanes

silanols

siloxanes

olefins

styryls

acrylics

norbornyls

cyclopropyls

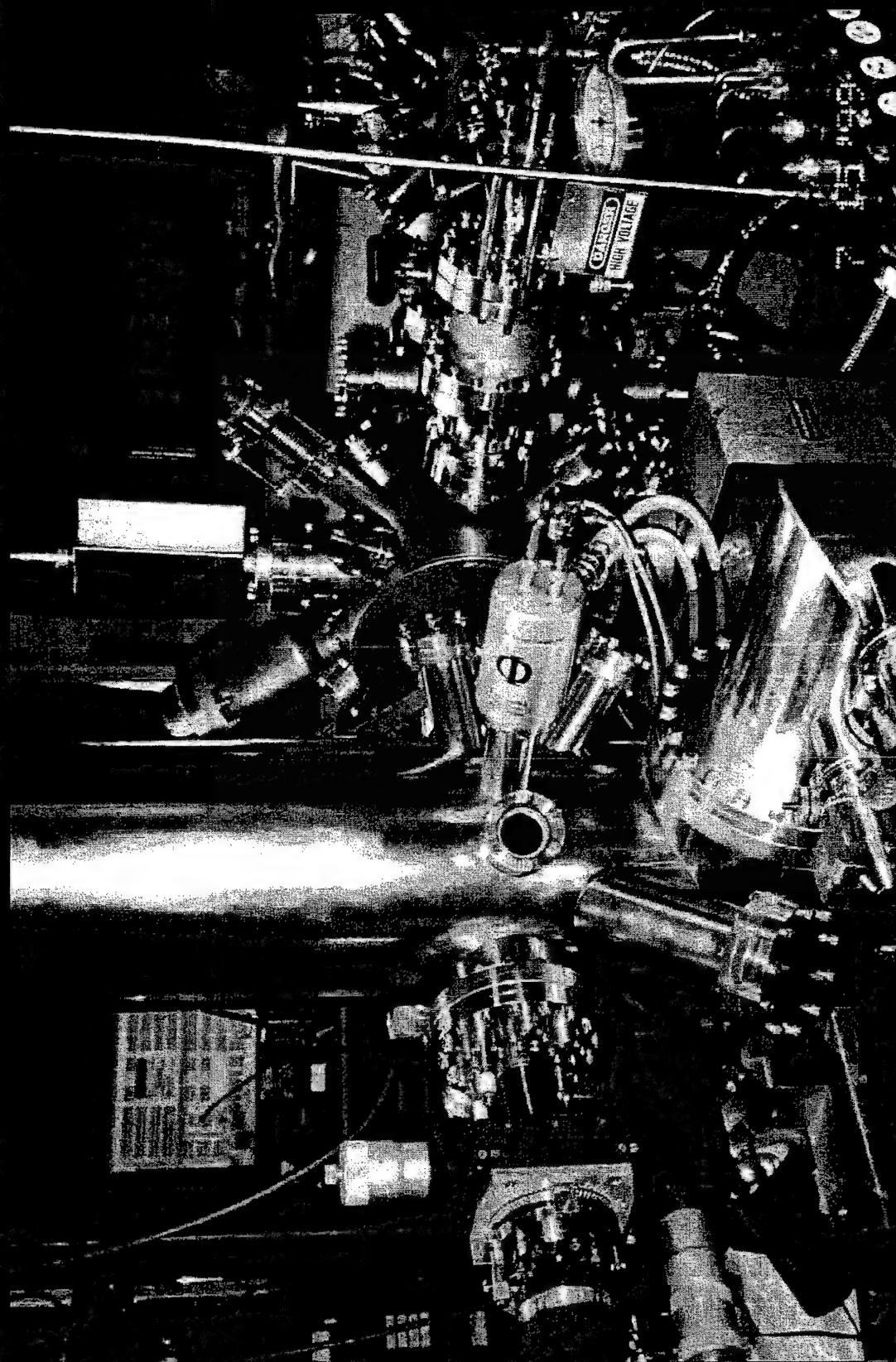
epoxies

- POSS-rubber*
- POSS-urethane*
- POSS-epoxy*
- POSS-phenolic*
- POSS-imide*
- POSS-teflon

monomers and polymers.

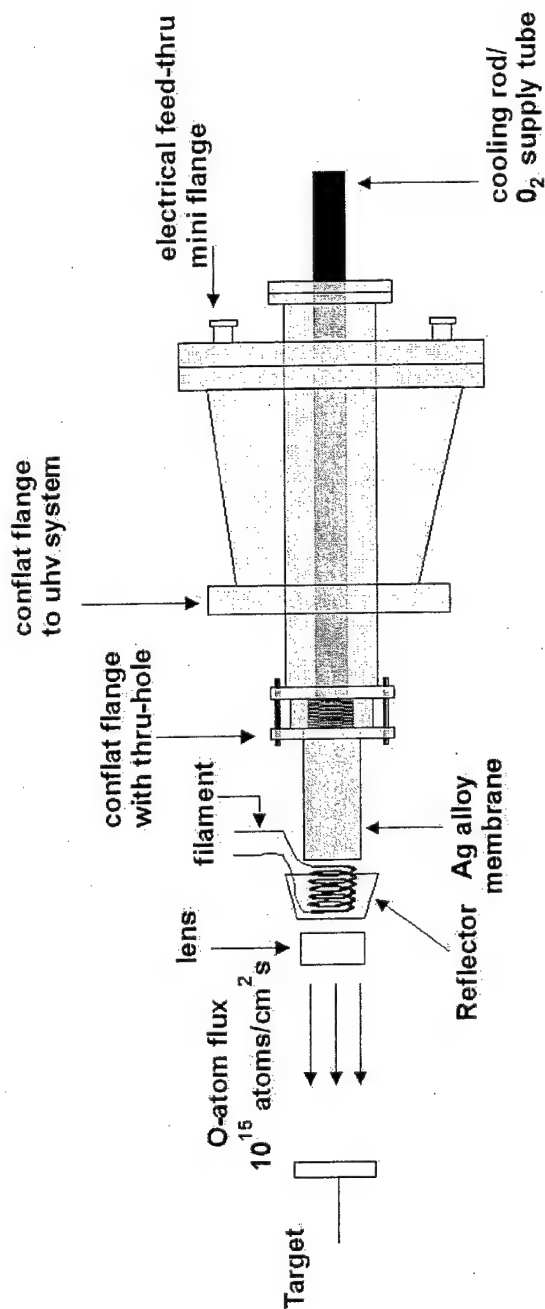
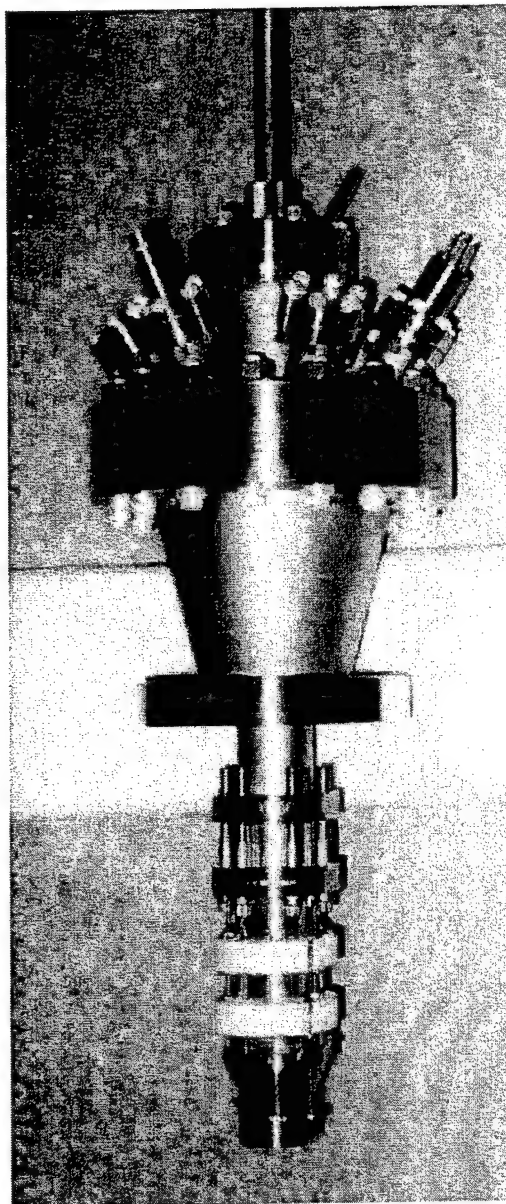


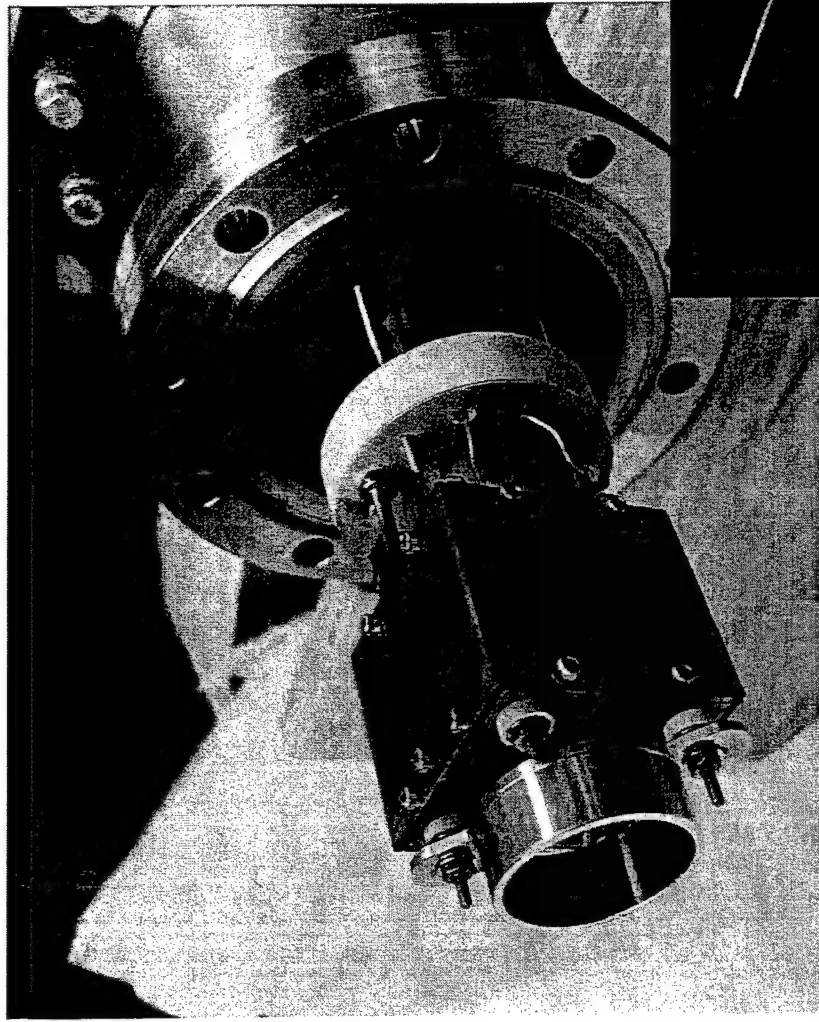
UF LEO Simulation Facility



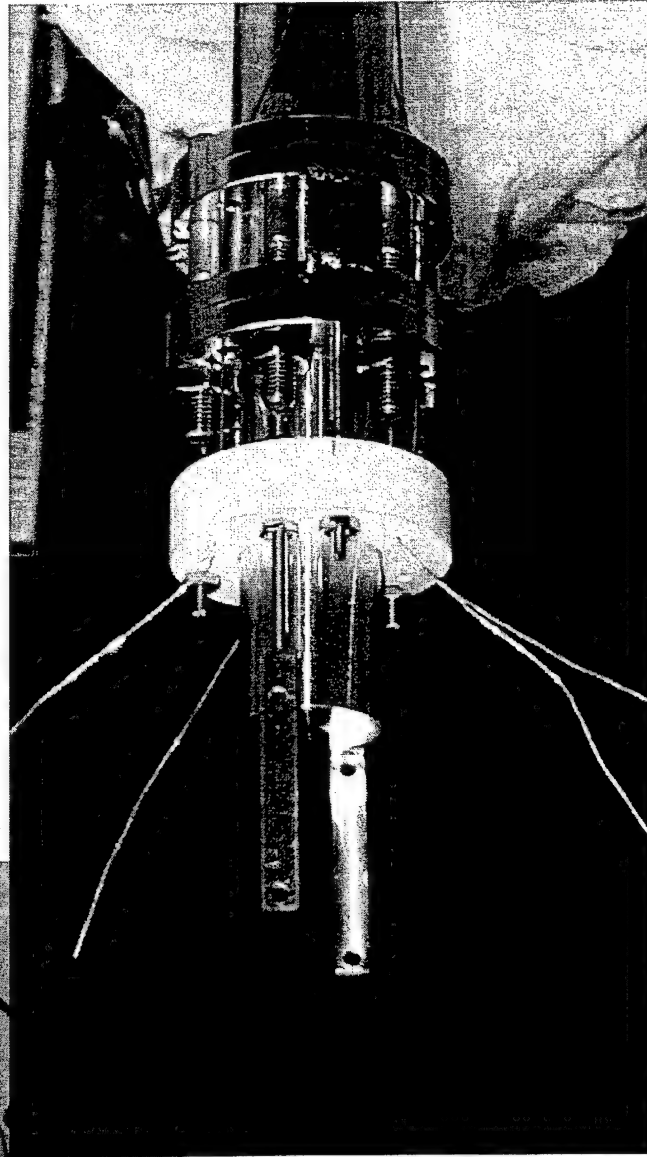


Oxygen Atom Source



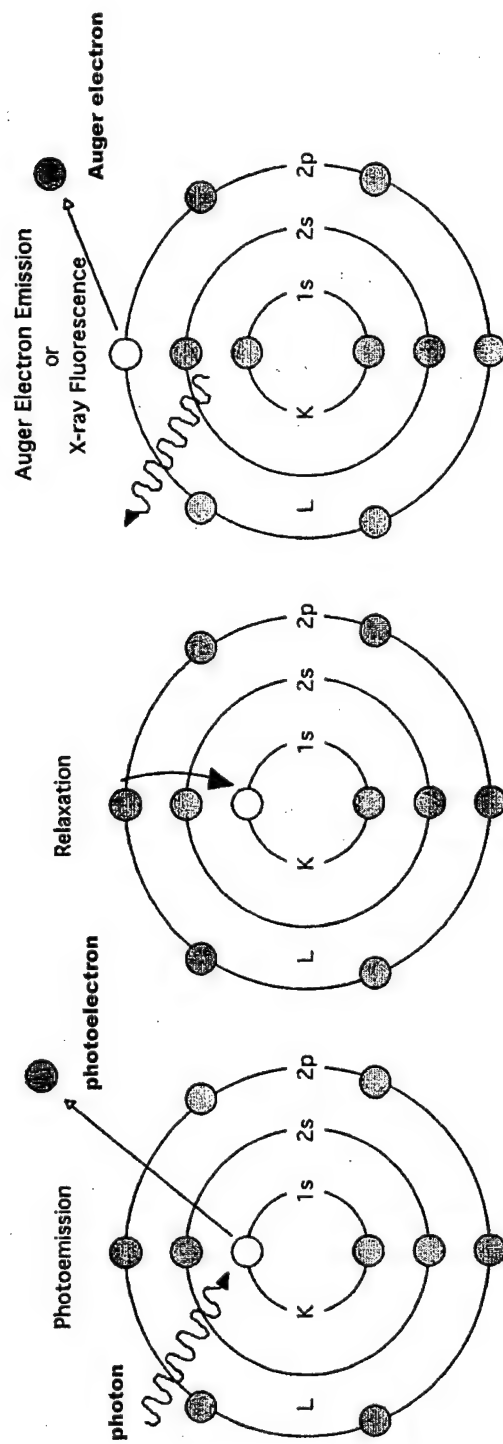


Improved reflector/lens assembly

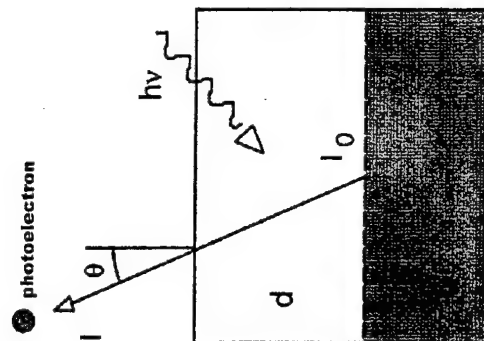
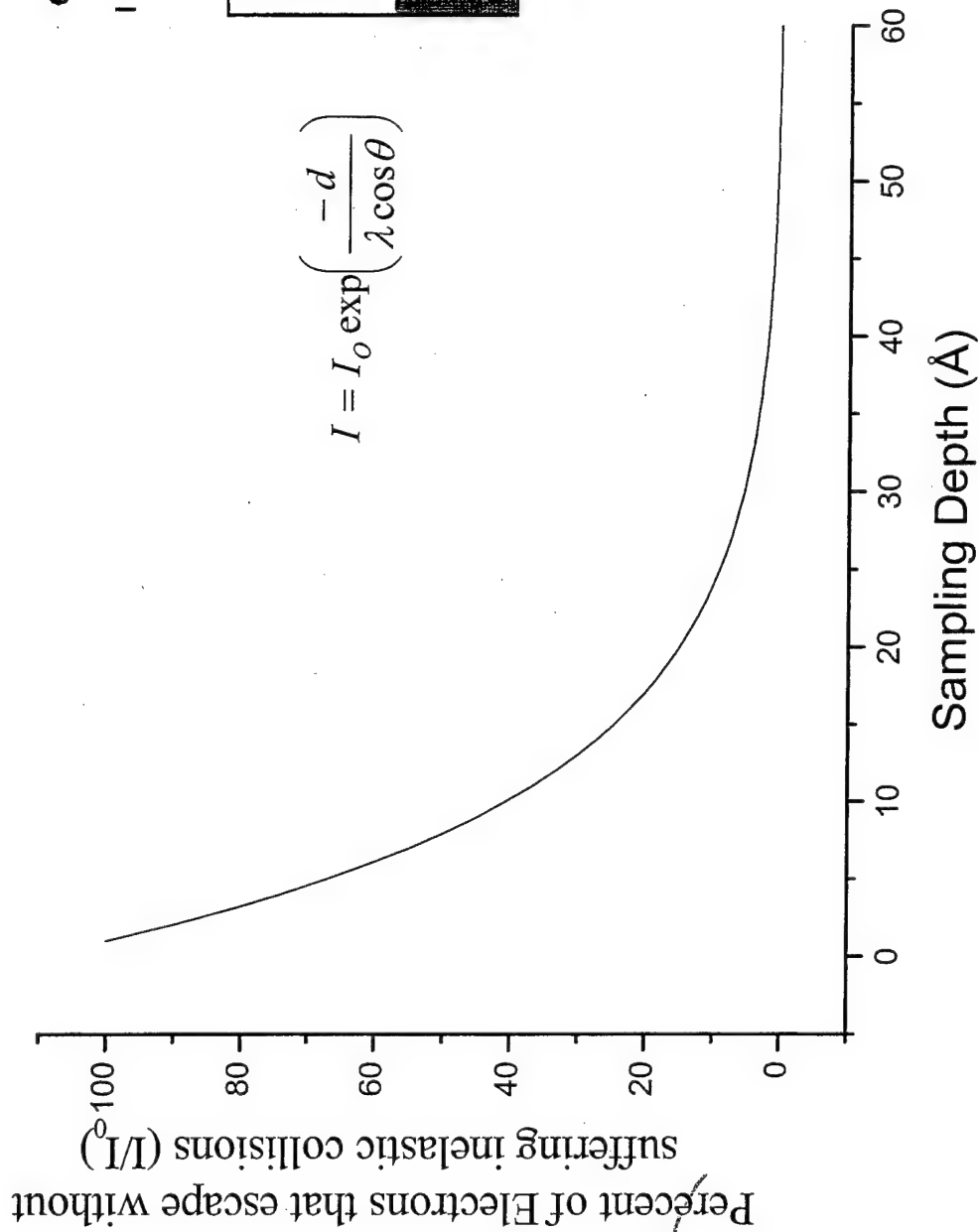


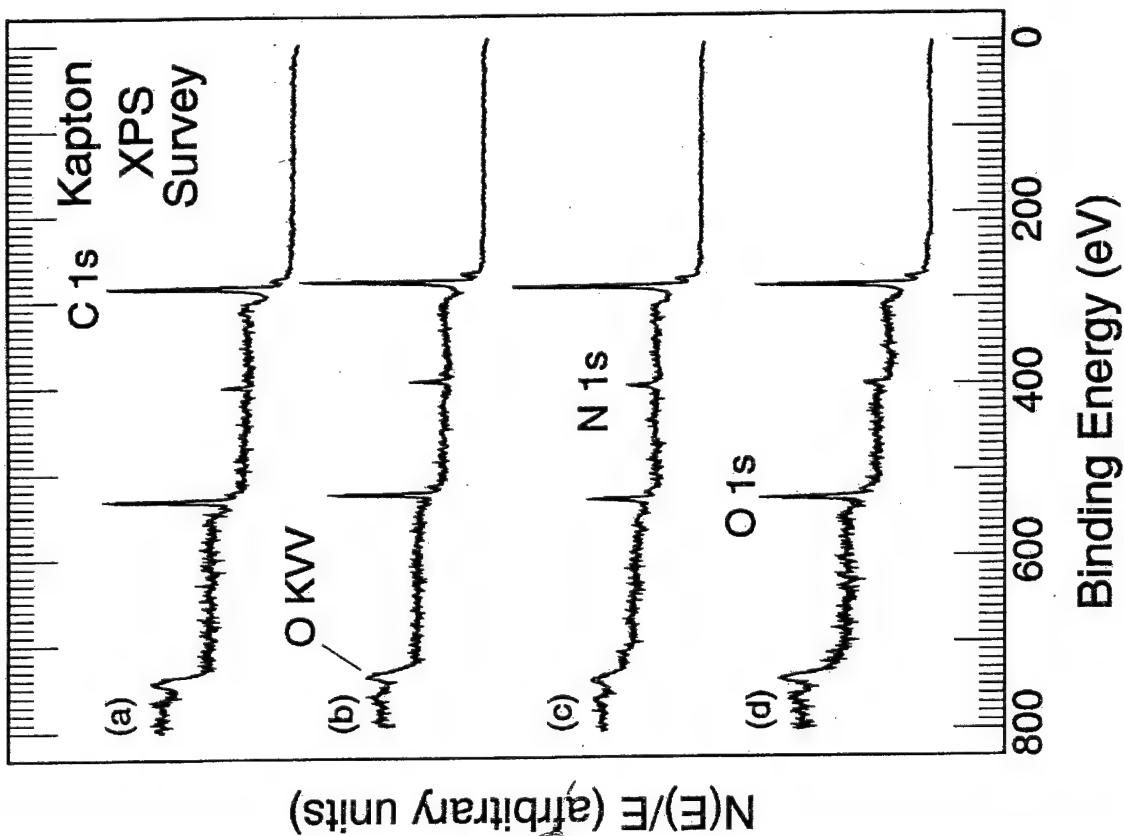
Reinforced membrane assembly

Photoemission process occurring during XPS



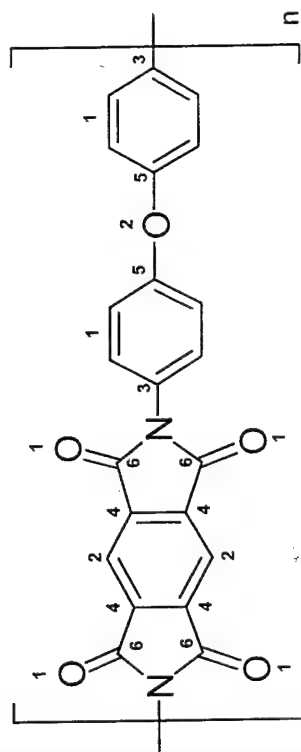
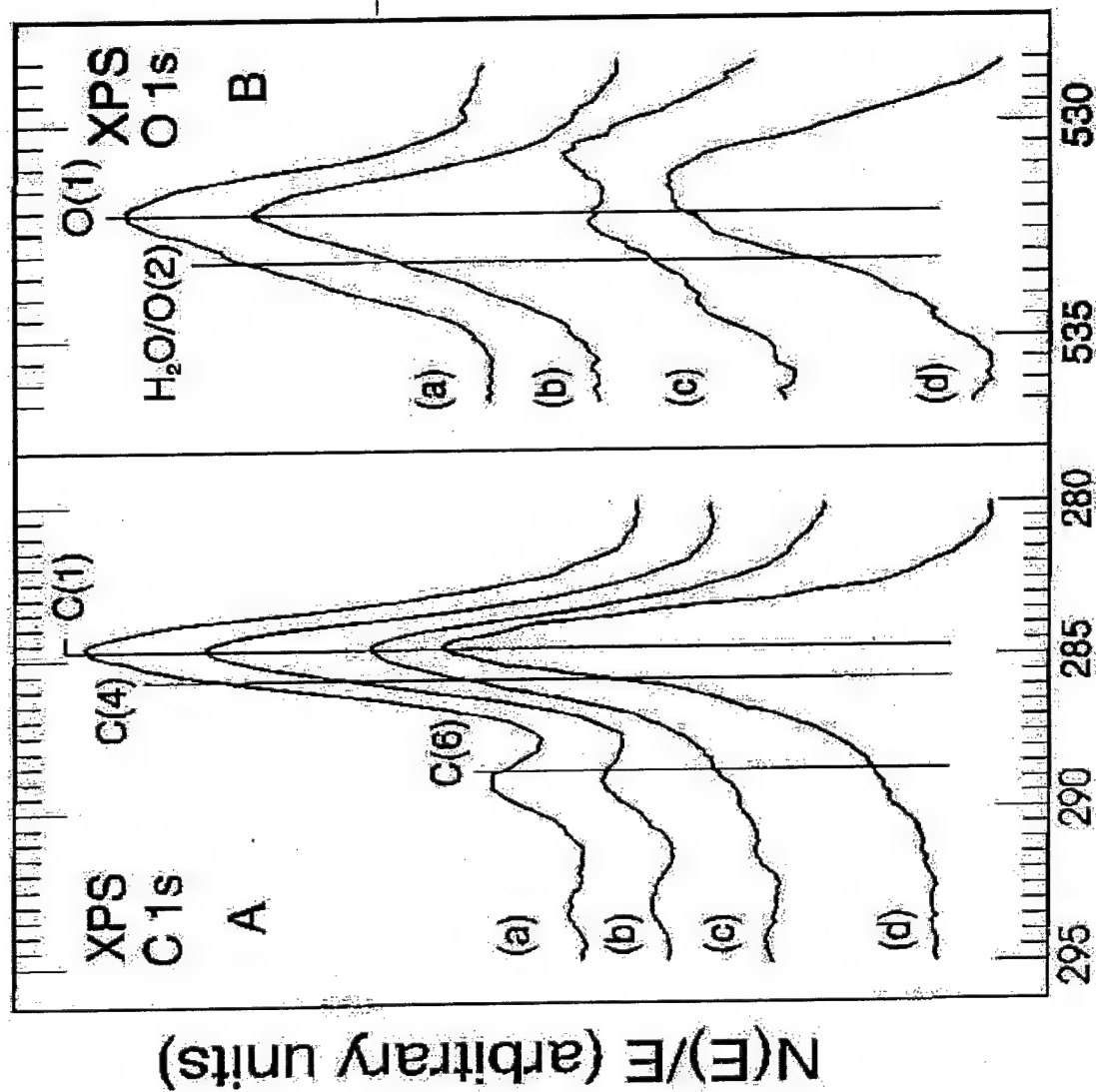
Sampling Depth of Photoelectron





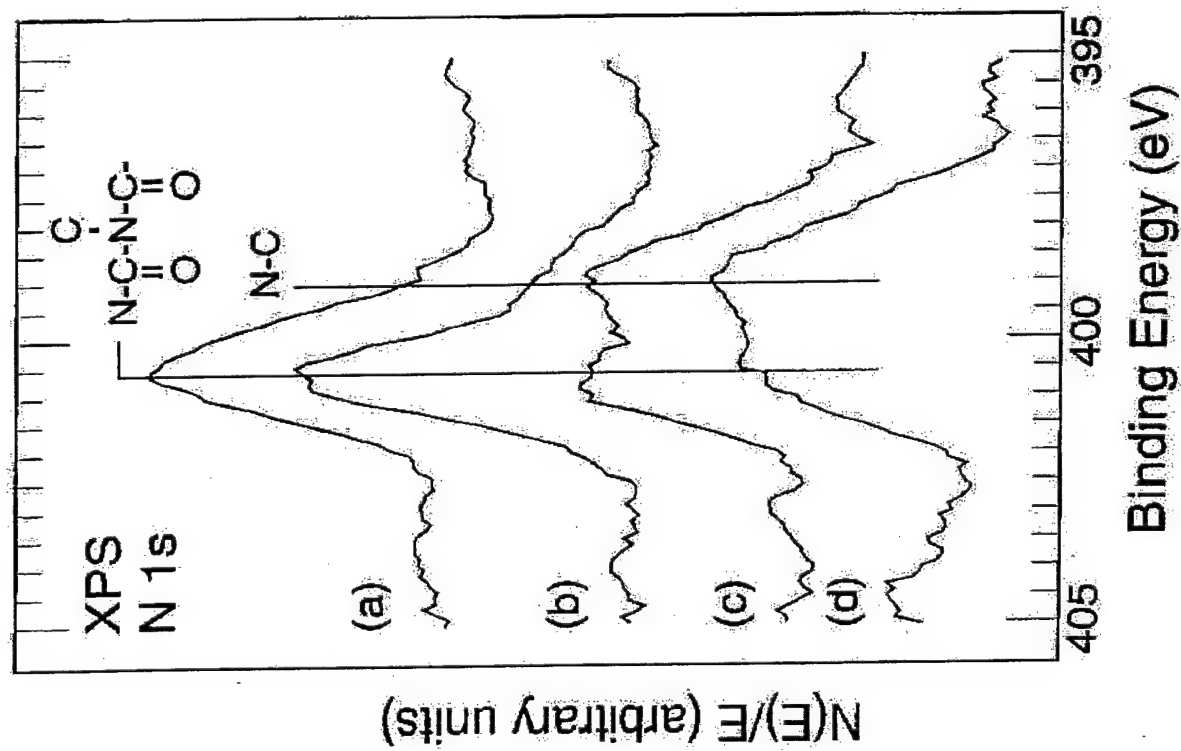
Grossman, E.; Wolan, J.T.; Mount, C.K.; Hoflund, G.B.; J. Spacecraft and Rockets, 36, No. 1, 75-78

XPS survey spectra obtained from a solvent-cleaned, Kapton film after (a) insertion into the vacuum system, (b) a 20-min, and (c) a 24-h exposure to the hyperthermal AO flux, and (d) a 3-hr air exposure following the 24-hr exposure.

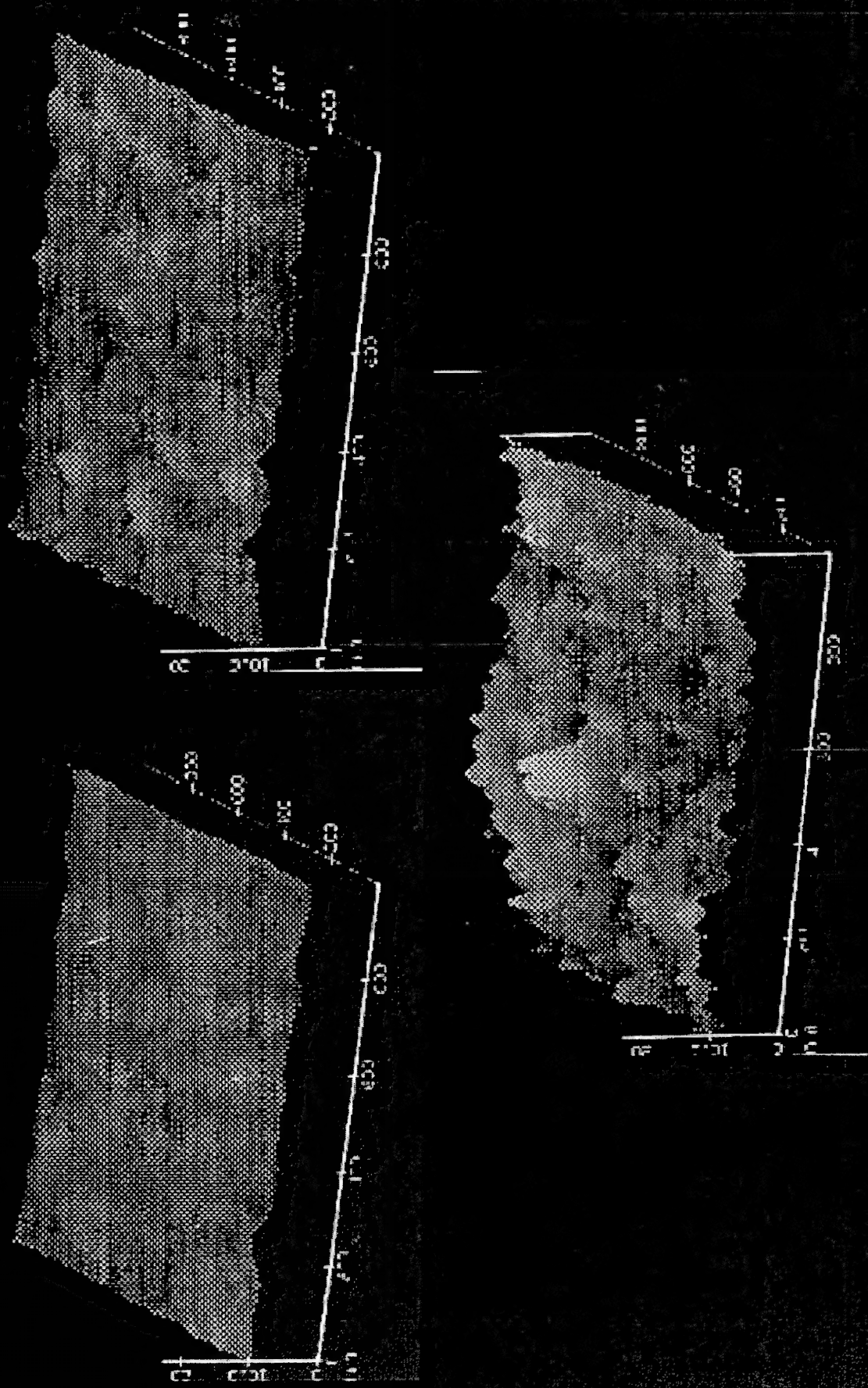


Binding Energy (eV)

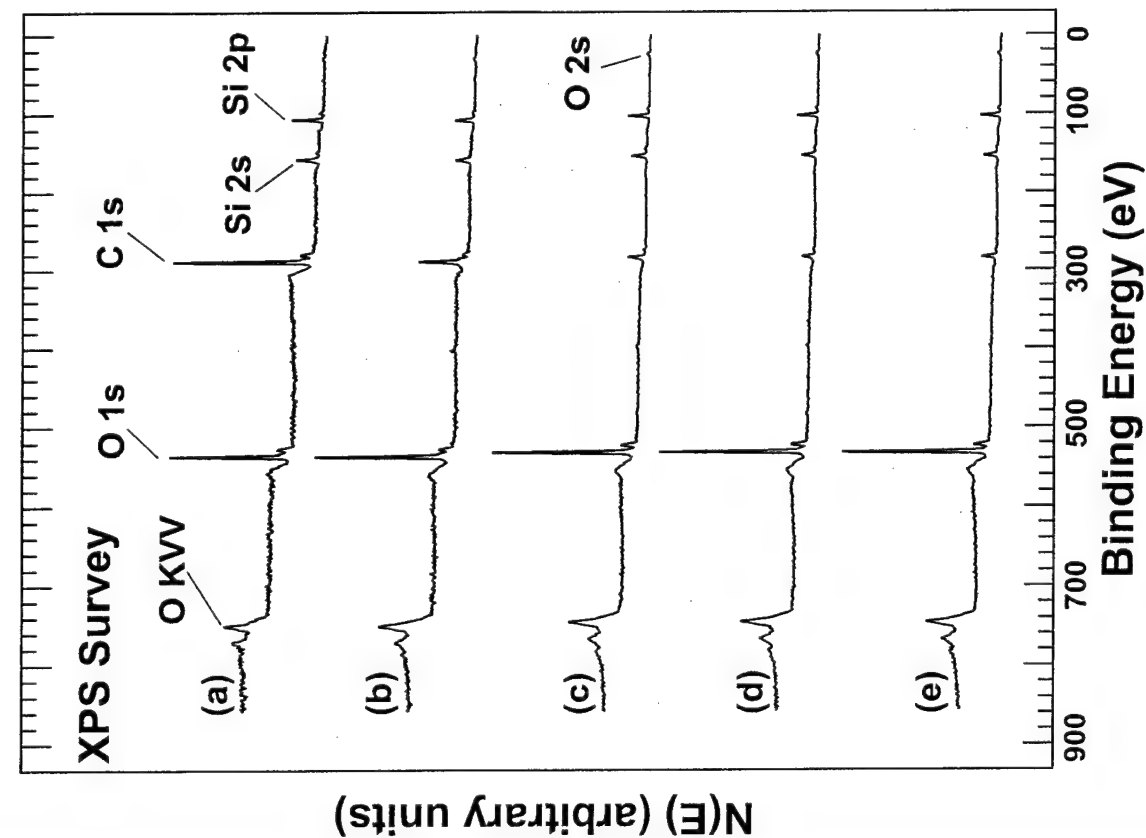
High Resolution C 1s and O 1s spectra obtained from a solvent-cleaned, Kapton film after (a) insertion into the vacuum system, (b) a 20-min, and (c) a 24-h exposure to the hyperthermal AO flux, and (d) a 3-hr air exposure following the 24-hr exposure.



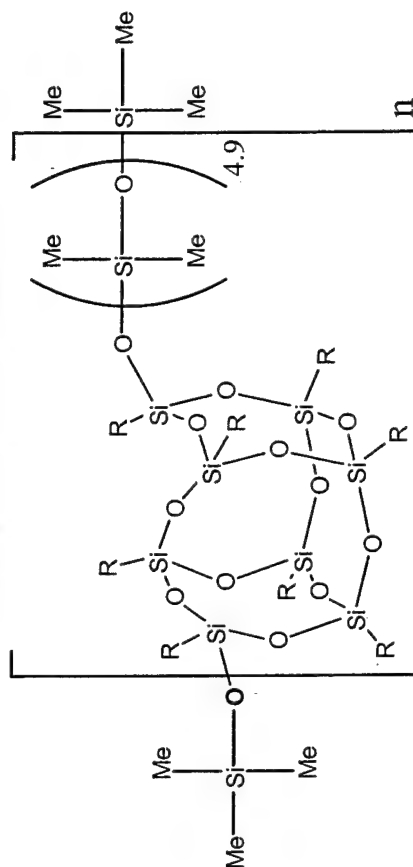
High Resolution N 1s spectra obtained from a solvent-cleaned, Kapton film after (a) insertion into the vacuum system, (b) a 20-min, and (c) a 24-h exposure to the hyperthermal AO flux, and (d) a 3-hr air exposure following the 24-hr exposure.



AFM images from a solvent-cleaned Kapton film after (a) insertion into the vacuum system, (b) a 20-min, and (c) a 24-hr exposure to hyperthermal AO flux.



POSS Siloxane

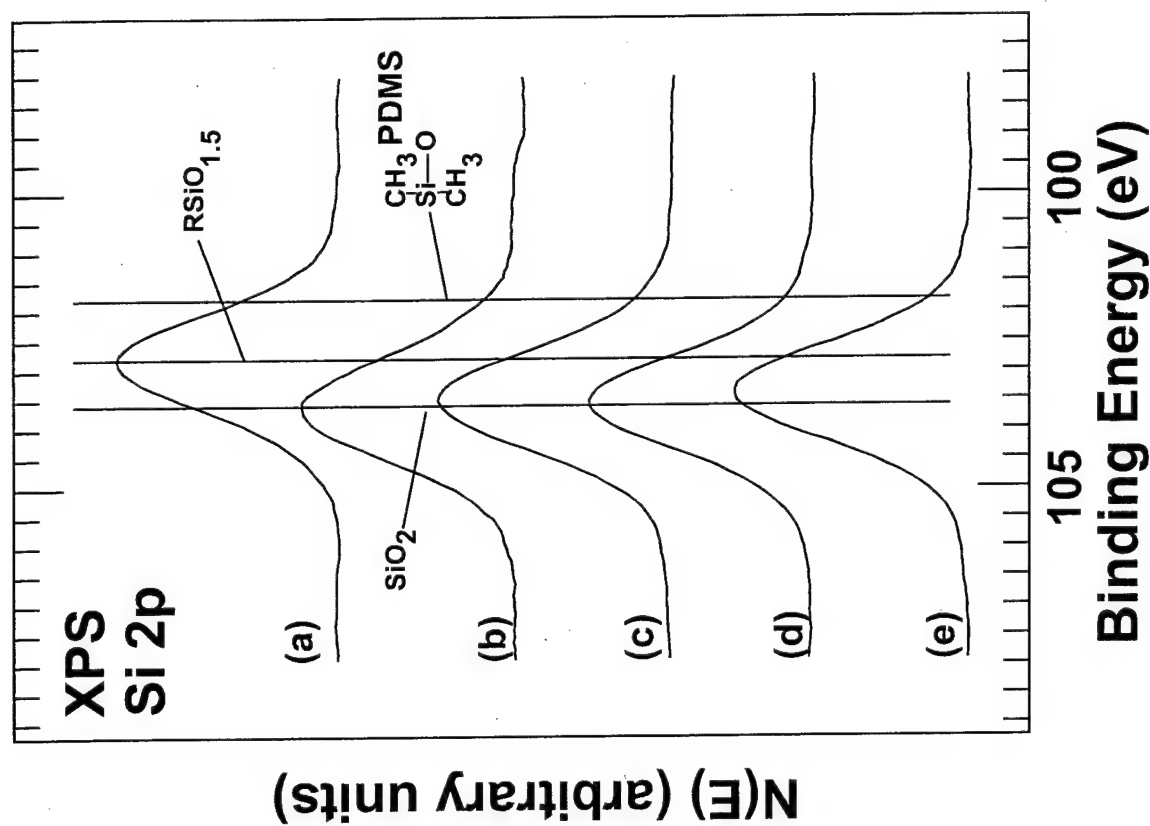


Composition, at %

Sample Treatment	O	C	Si
As entered	18.5	65.0	16.6
2.0 hr	33.8	48.4	17.8
24.6 hr	49.1	22.1	28.8
63.0 hr	55.7	16.3	28.0
4.8 hr air	52.8	19.5	27.7

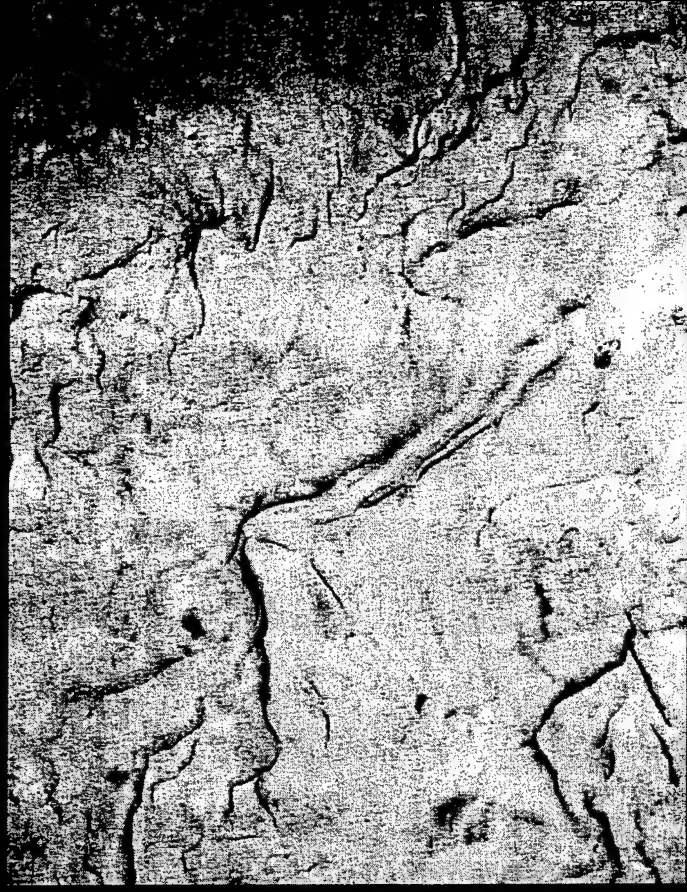
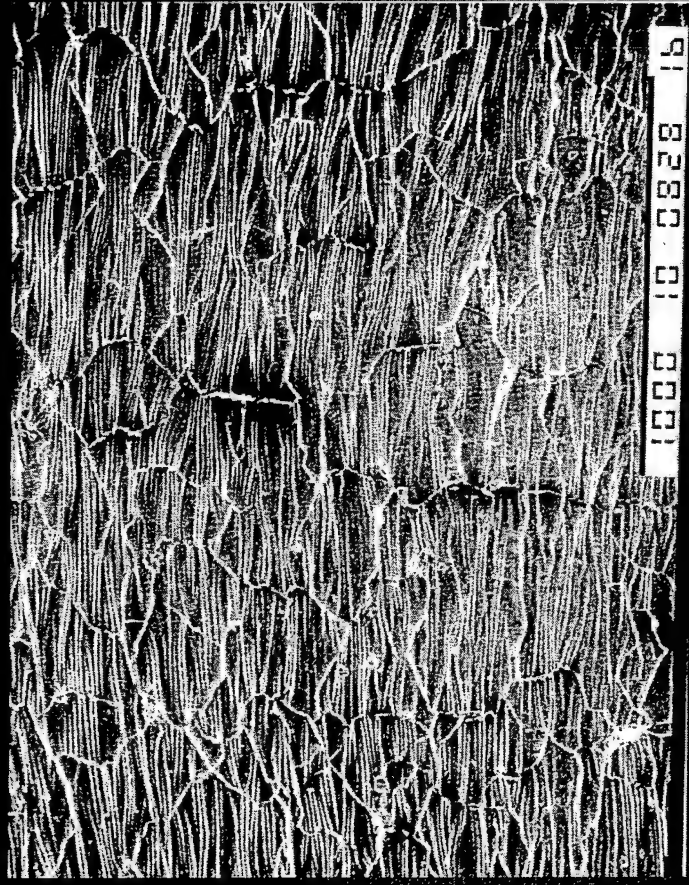
Gonzalez, R. I., Phillips, S. H., Hoflund, G. B., *J. of Spacecraft and Rockets*, Vol 37, No. 4, 2000, pp. 463-467.

XPS survey spectra obtained from a solvent-cleaned, POSS-PDMS film (a) after insertion into the vacuum system, (b), after a 2-hr (c) 24.6-hr and (d) 63-hr exposure to the hyperthermal AO flux, and (e) 4.75-hr air exposure following the 63-hr AO exposure.



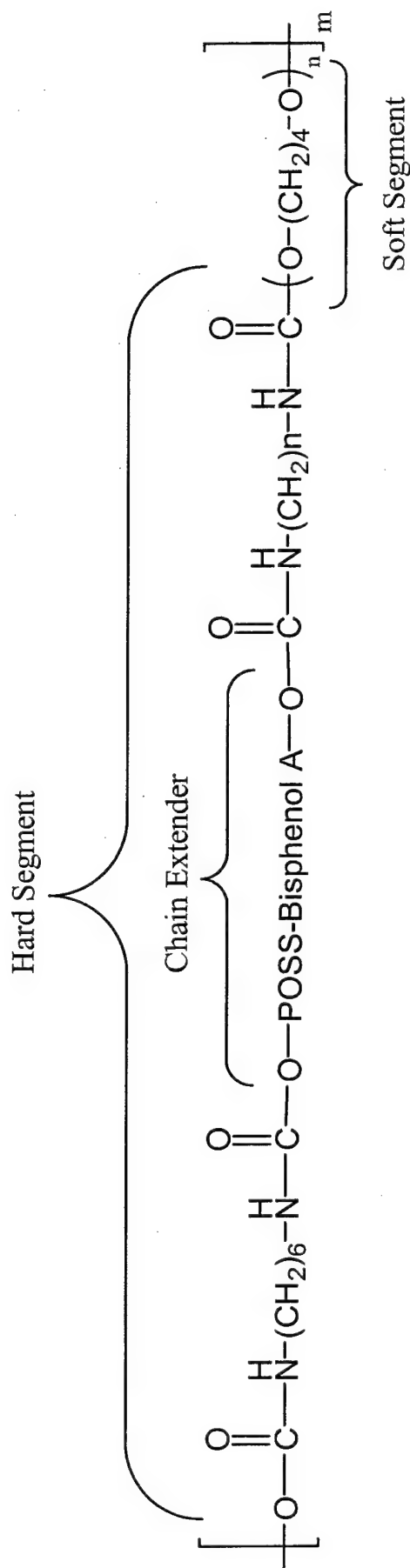
High Resolution Si 2p spectra obtained from a solvent-cleaned, POSS-PDMS film (a) after insertion into the vacuum system, (b), after a 2-hr (c) 24.6-hr and (d) 63-hr exposure to the hyperthermal AO flux, and (e) 4.75-hr air exposure following the 63-hr AO exposure.

SEM of POSS-Siloxane Copolymer



SEM of (a) unexposed and (b) exposed POSS-siloxane copolymer surfaces. The simulated LEO exposure “healed” the micro-cracks present initially in the POSS-siloxane sample.

Properties of POSS-Urethanes



Polymer	Melt Transition °C	T _{dec} °	Char Yield%	Appearance
0% POSS*	-49, 22	274 °C	1.4	Viscous Fluid
29% POSS*	201	372 °C	16.0	Solid Rubber
43% POSS*	260, 320	344 °C	20.0	Solid Rubber

Moduli for POSS BPA and TMP Urethanes

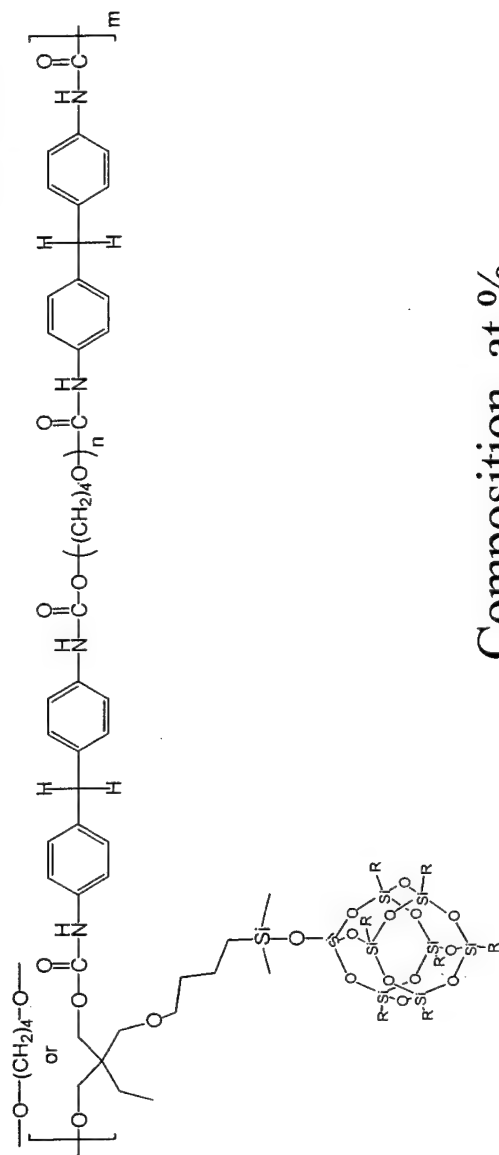


0 wt.% POSS	0.04 Mpa	0 wt.% POSS	0.01 Mpa
17 wt.% POSS	0.42 Mpa	17 wt.% POSS	0.14 Mpa
34 wt.% POSS	1.06 Mpa	34 wt.% POSS	0.39 Mpa

Samples were stretched to 400% elongation

All polymers were prepared through melt polymerization

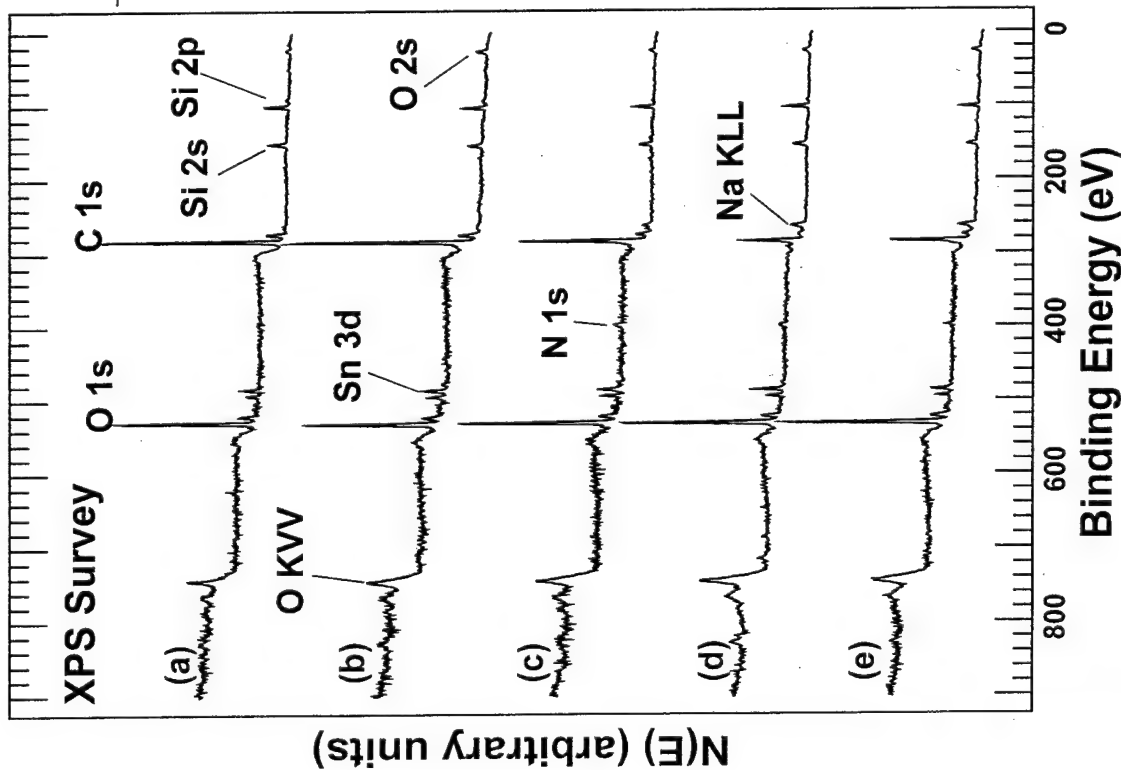
60 wt % POSS-Polyurethane



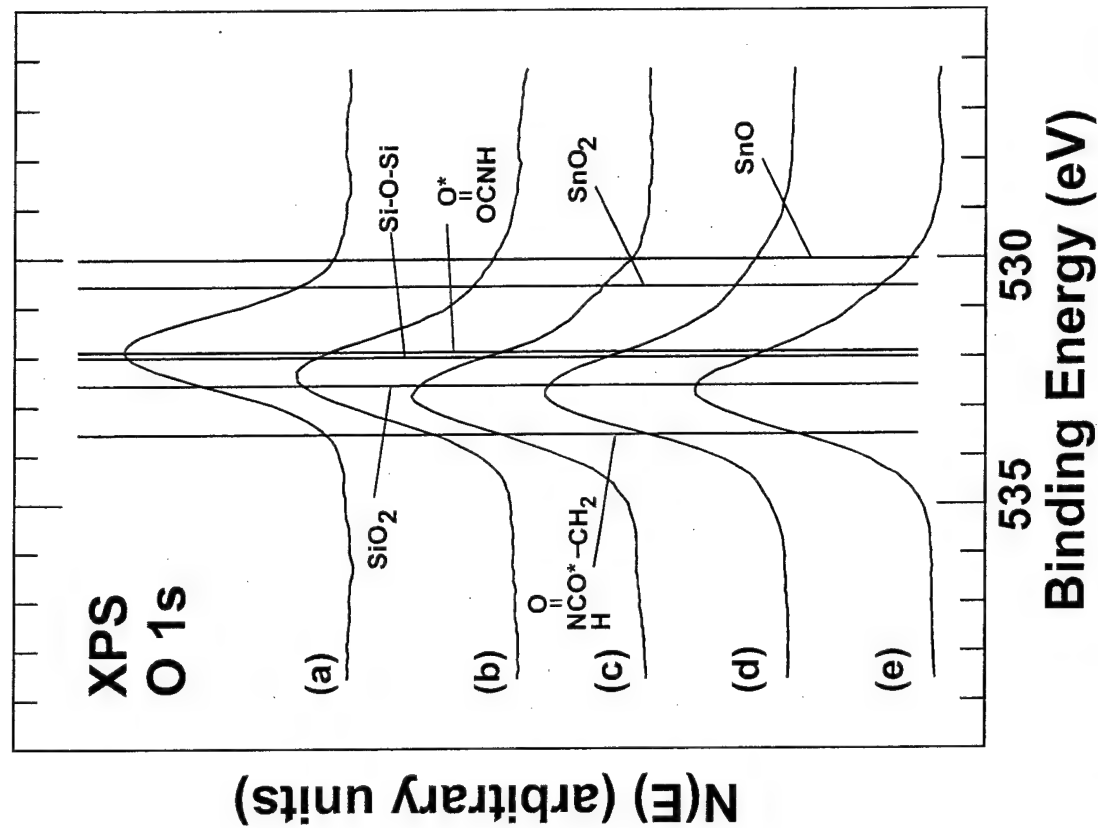
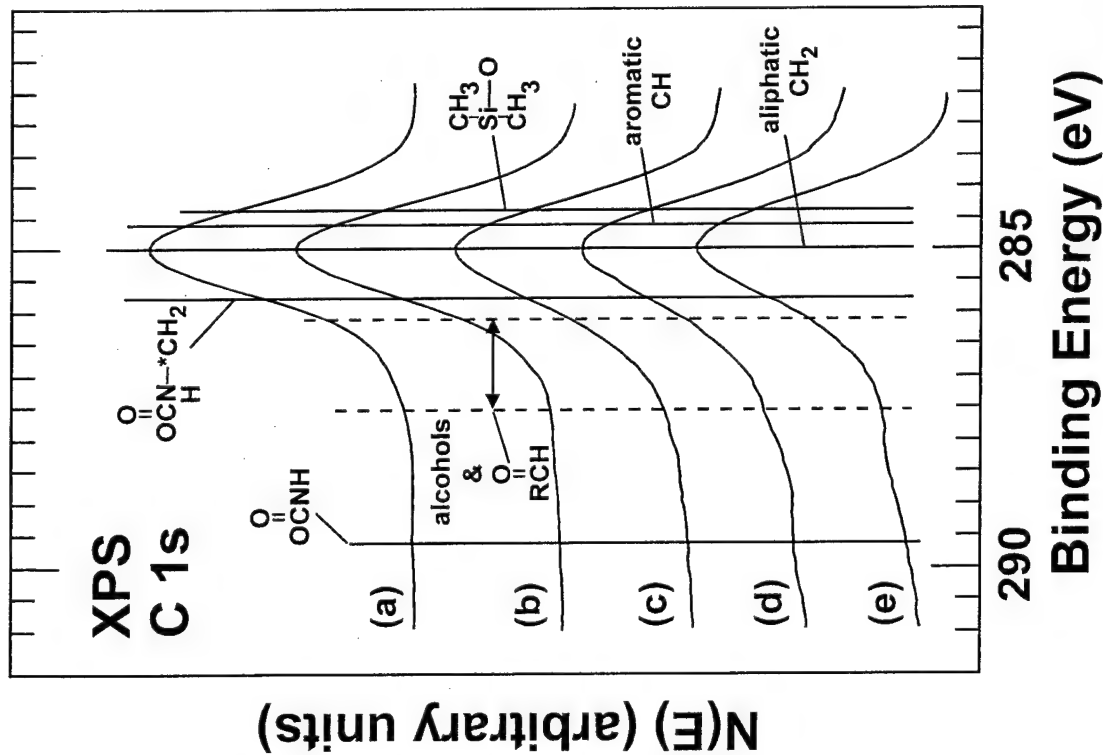
Composition, at %

Sample Treatment	O	C	Si	Sn	Na	N
As entered	18.2	70.1	11.3	0.4	-	-
2.0-hr	17.5	70.2	11.2	0.7	0.4	-
24.0-hr	23.7	58.2	13.2	0.9	1.4	2.6
63.0-hr	35.3	37.3	20.4	1.3	3.0	2.7
3.3-h air	31.6	48.5	14.6	1.0	2.7	1.6

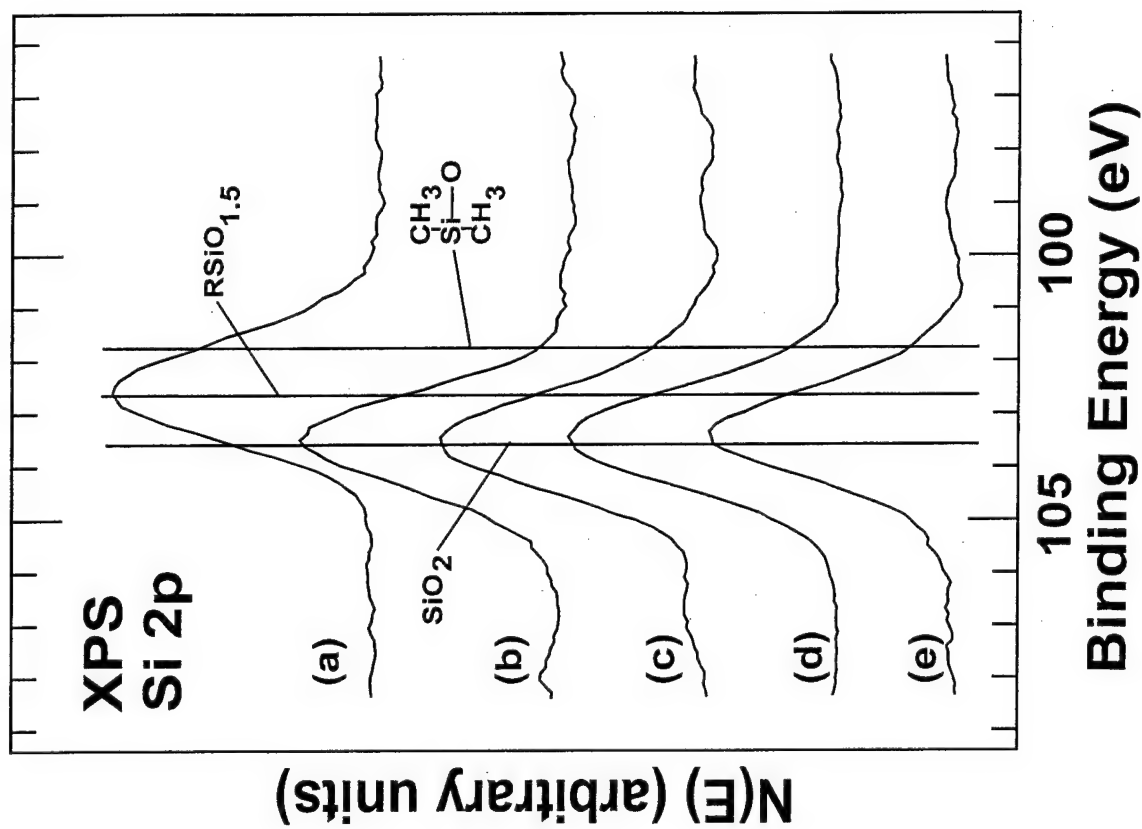
Phillips, S. H., Hoflund, G. B., Gonzalez, R. I., 45th International SAMPE Symposium, 2000, Vol. 45, No. 2, pp. 1921-1931.



XPS Survey Spectra from a 60 wt% POSS-PU (a) after insertion into the vacuum system, (b) after a 2-hr (c) 24-hr and (d) 63-hr exposure to the hyperthermal AO flux, and (e) 3.3-hr air exposure following the 63-hr exposure.

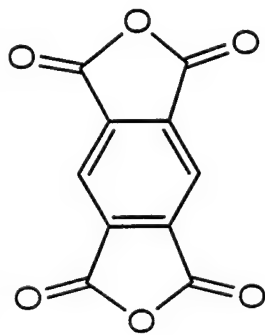


High Resolution C 1s and O 1s spectra from a 60 wt% POSS-PU (a) after insertion into the vacuum system, (b) after a 2-hr (c) 24-hr and (d) 63-hr exposure to the hyperthermal AO flux, and (e) 3.3-hr air exposure following the 63-hr exposure.

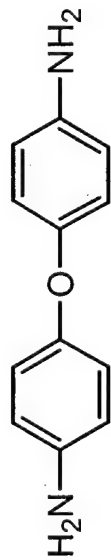


High Resolution Si 2p spectra from a 60 wt% POSS-PU (a) after insertion into the vacuum system, (b) after a 2-hr (c) 24-hr and (d) 63-hr exposure to the hyperthermal AO flux, and (e) 3.3-hr air exposure following the 63-hr exposure.

POSS-Kapton Polyimides



PMDA



ODA

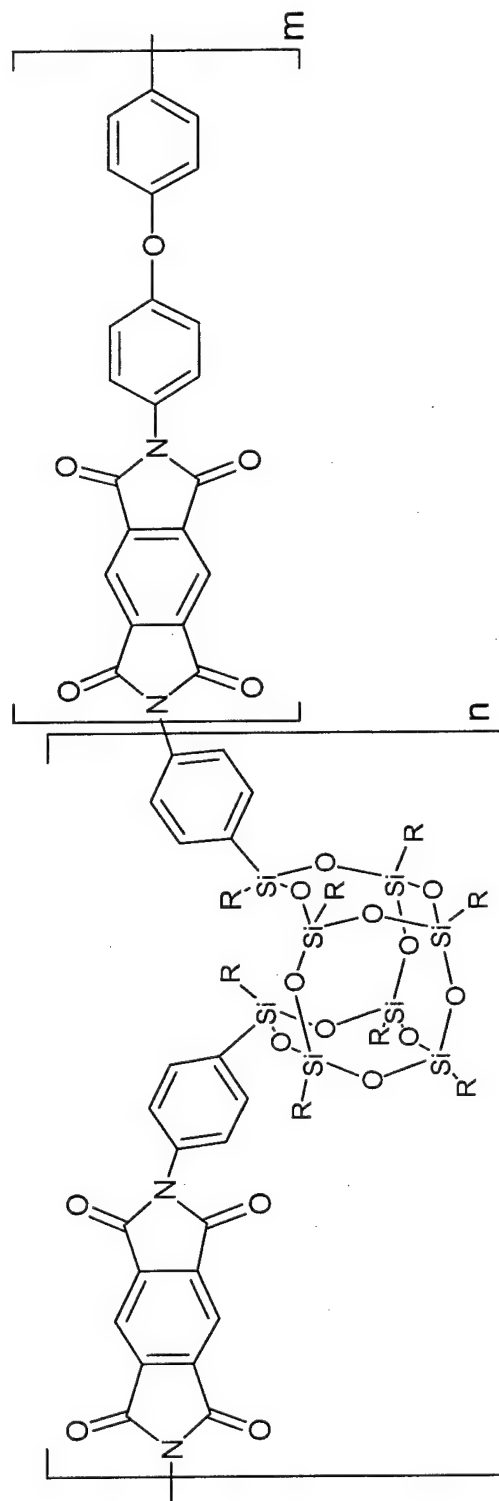
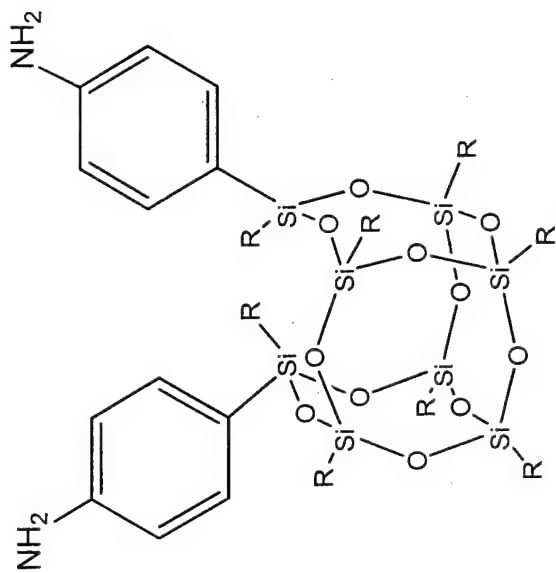


Table 2. AFRL Kapton Tensile Properties Calculated with the Average Sample Thickness.

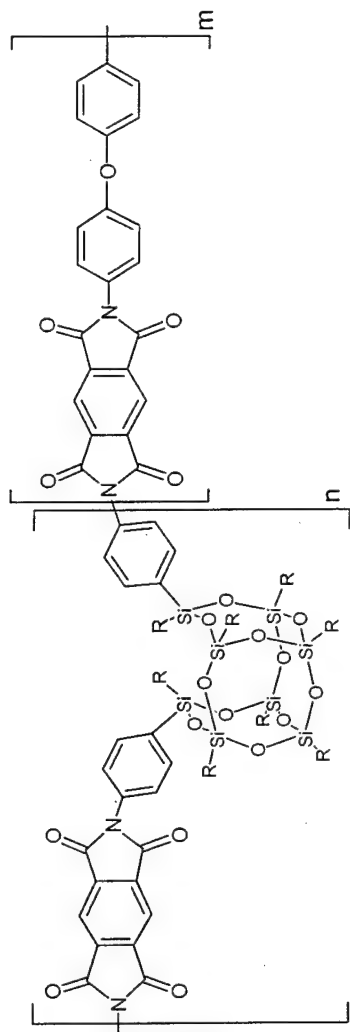
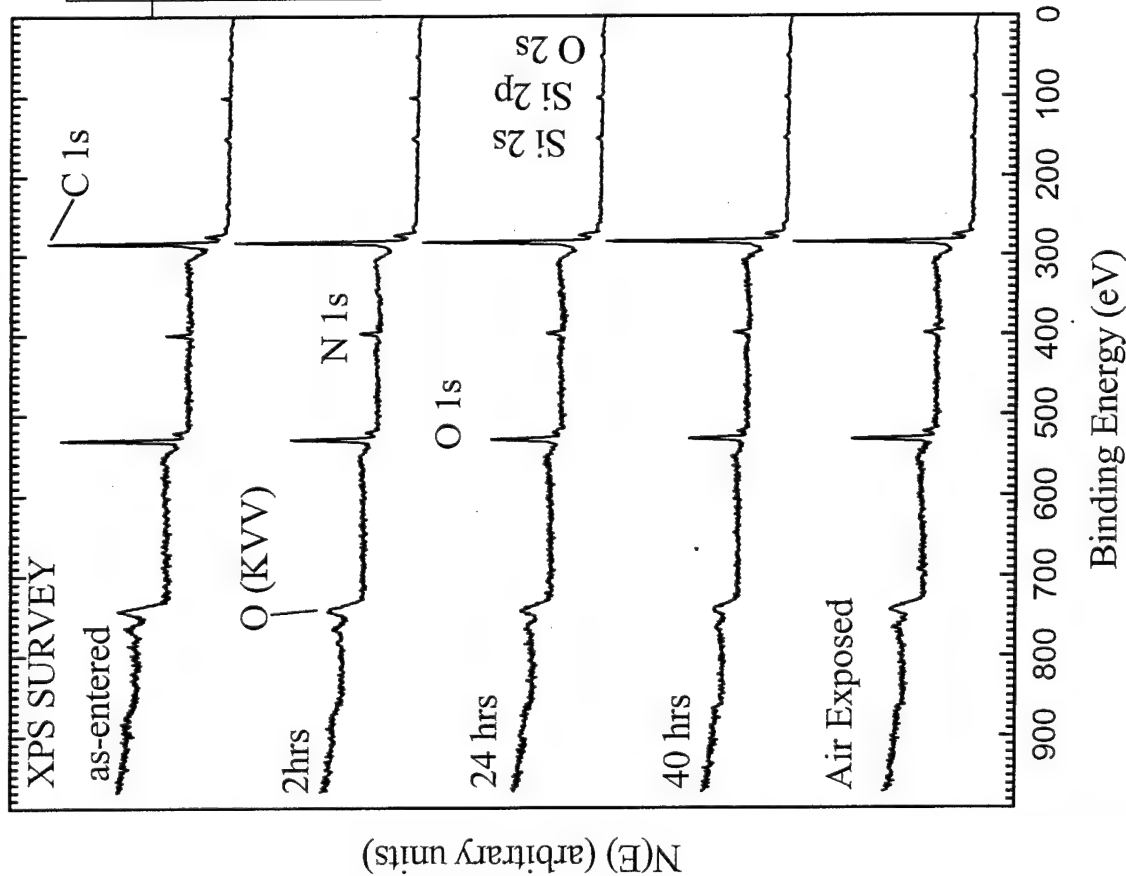
Sample No.	Young's Modulus, Ksi	Ultimate Tensile Strength, Ksi	Failure Strain, %
Baseline AFRL Kapton without POSS			
Average	348	9.0	4.86
AFRL Kapton doped with 10 wt.% POSS			
Average	370	10.8	6.59
AFRL Kapton doped with 20 wt.% POSS			
Average	321	7.5	3.89

Glass Transition Temperatures of POSS-Polyimides
Measured by DMA
Heating Rate: 10°C per Minute

% POSS	Tg in Air (°C)	Tg in Nitrogen (°C)
0	386	389
10	380	381
20	370	373

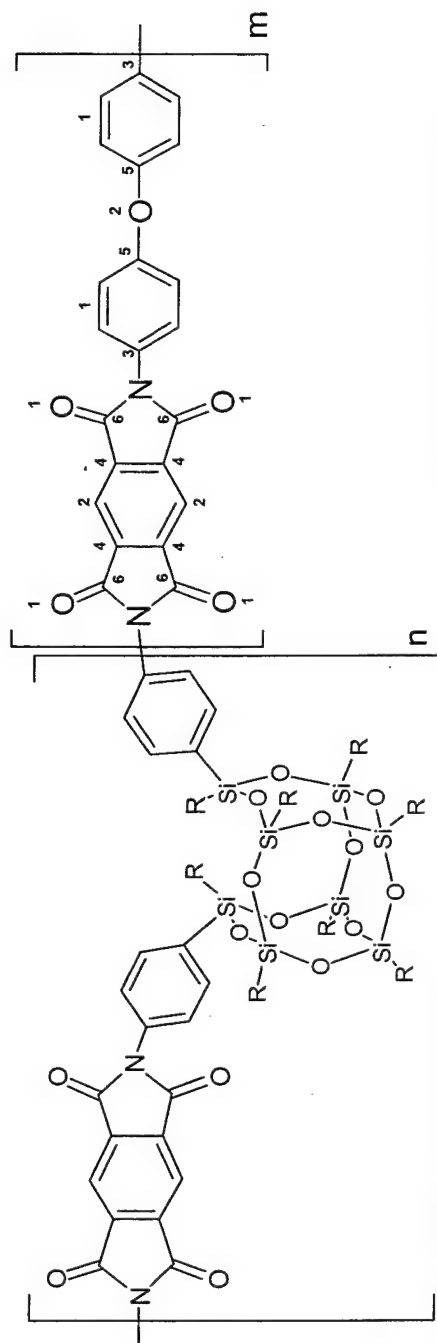
Note: DuPont claims that the Tg of Kapton H is in the range of 360 - 410°C, "depending on how it is measured."

10 wt% POSS Kapton

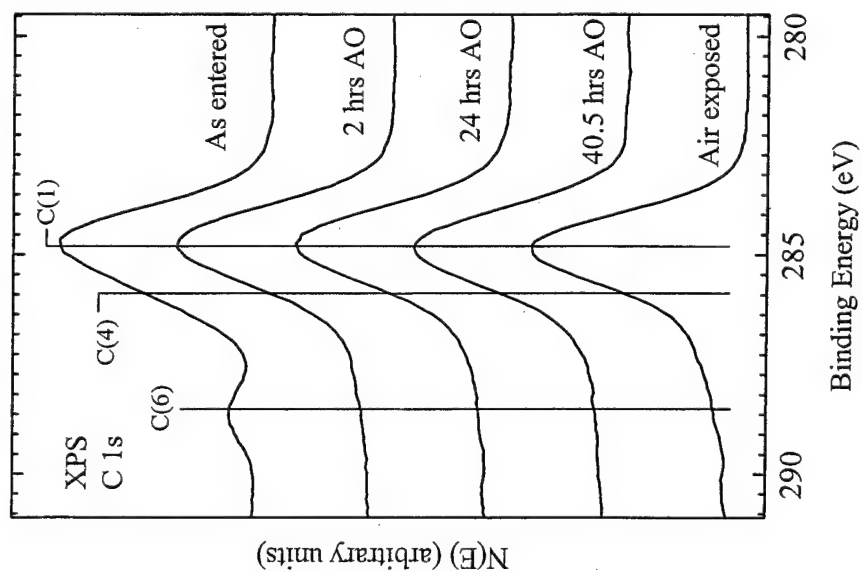
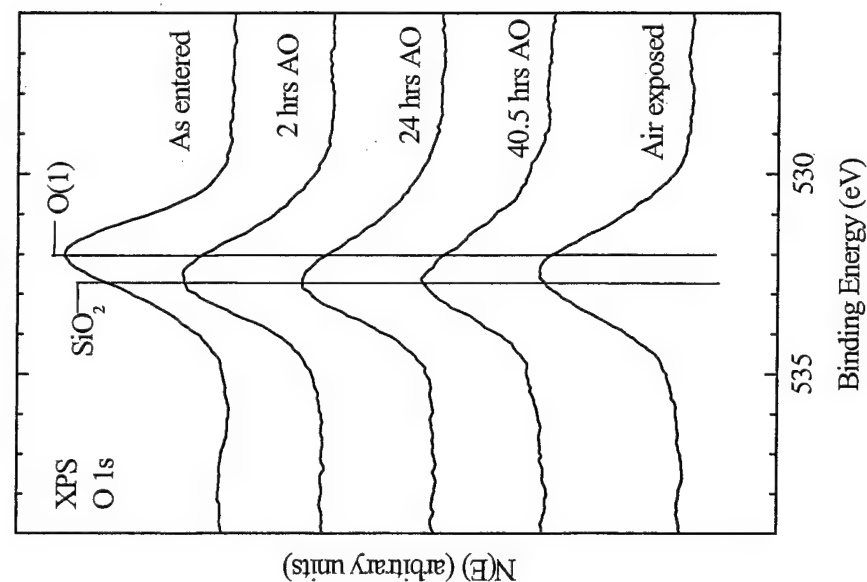


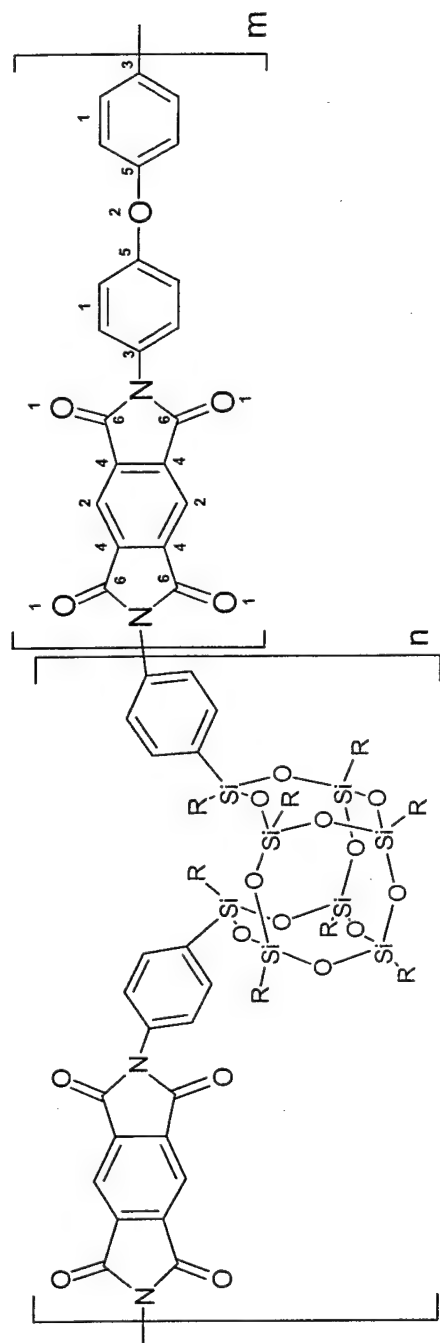
Composition, at %

Sample Treatment	O	C	N	Si	O/Si
As entered	15.9	74.5	4.9	4.6	3.4
2.0-hr	14.3	72.6	8.2	4.9	2.9
24.0-hr	11.1	79.6	4.9	4.4	2.5
40.0-hr	9.1	81.5	5.6	3.7	2.4
Air exposed	13.9	76.8	5.8	3.5	3.9

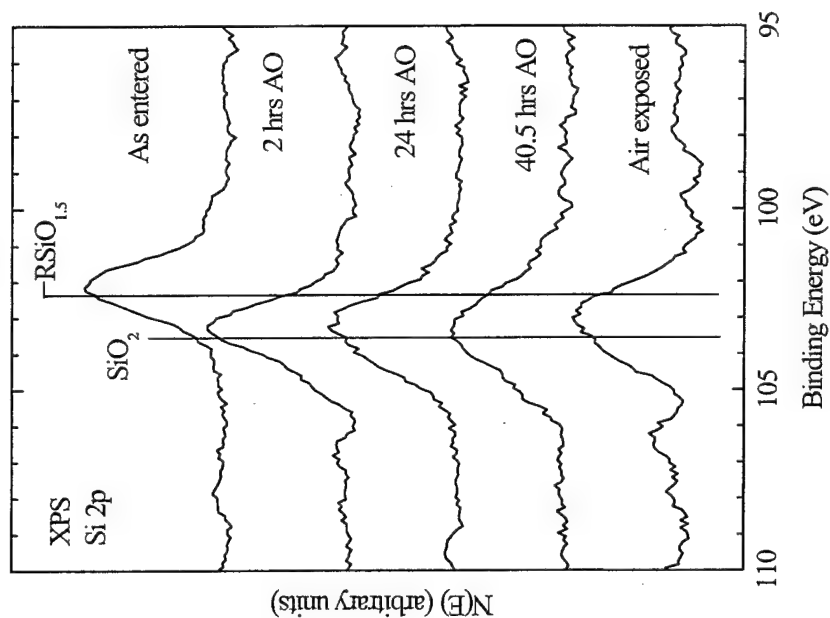
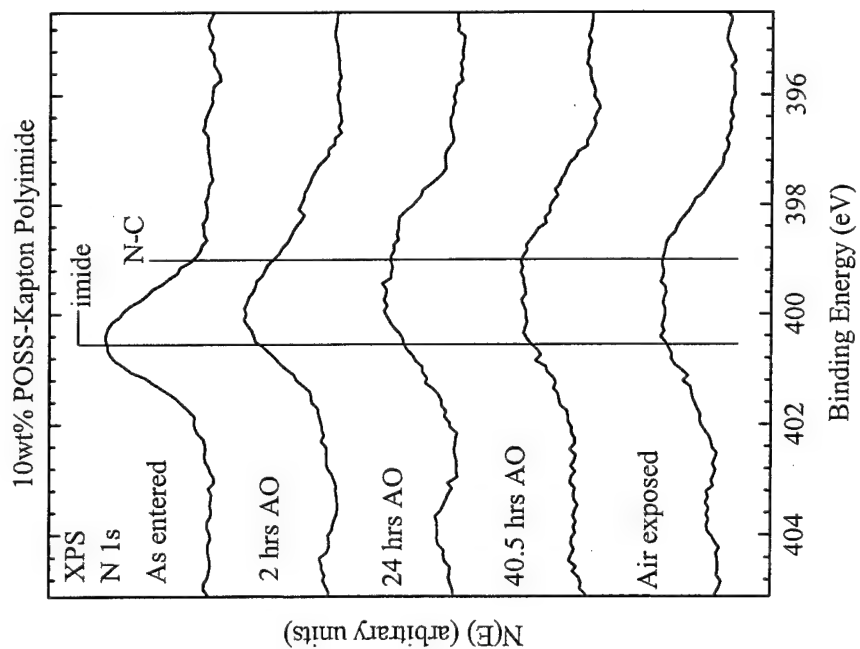


10wt% POSS-Kapton Polyimide

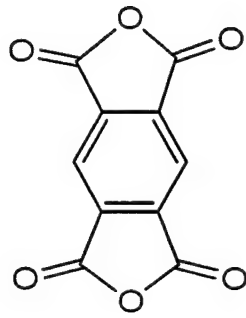
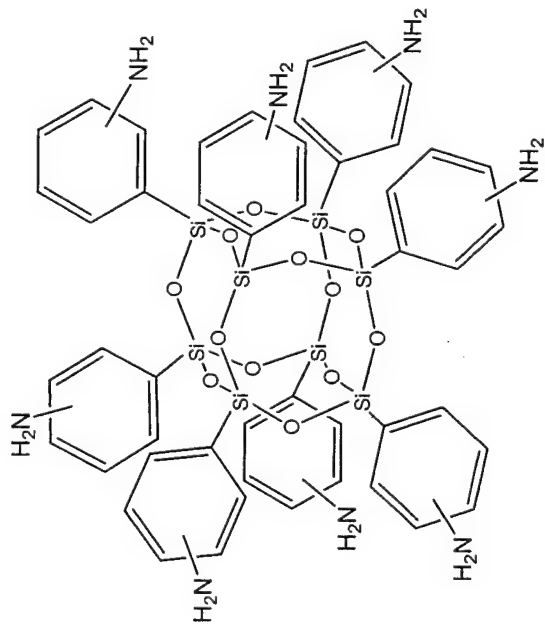




10wt% POSS-Kapton Polyimide

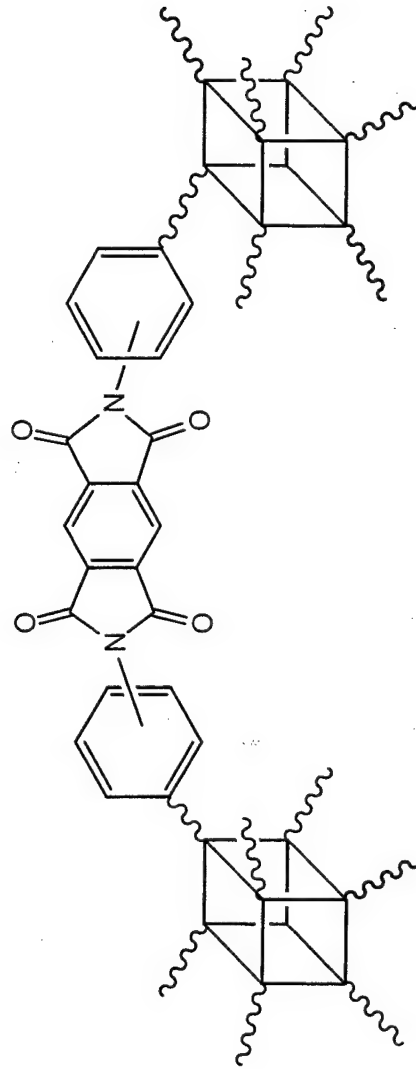


Octaphenylamino Silsesquioxane Imide Resin



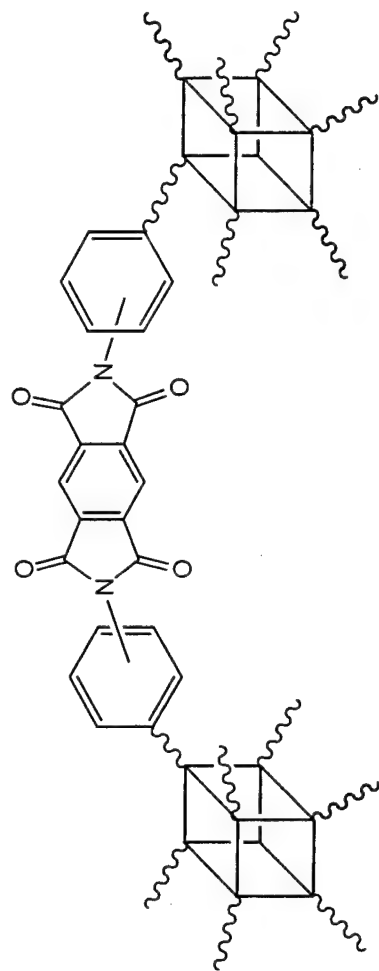
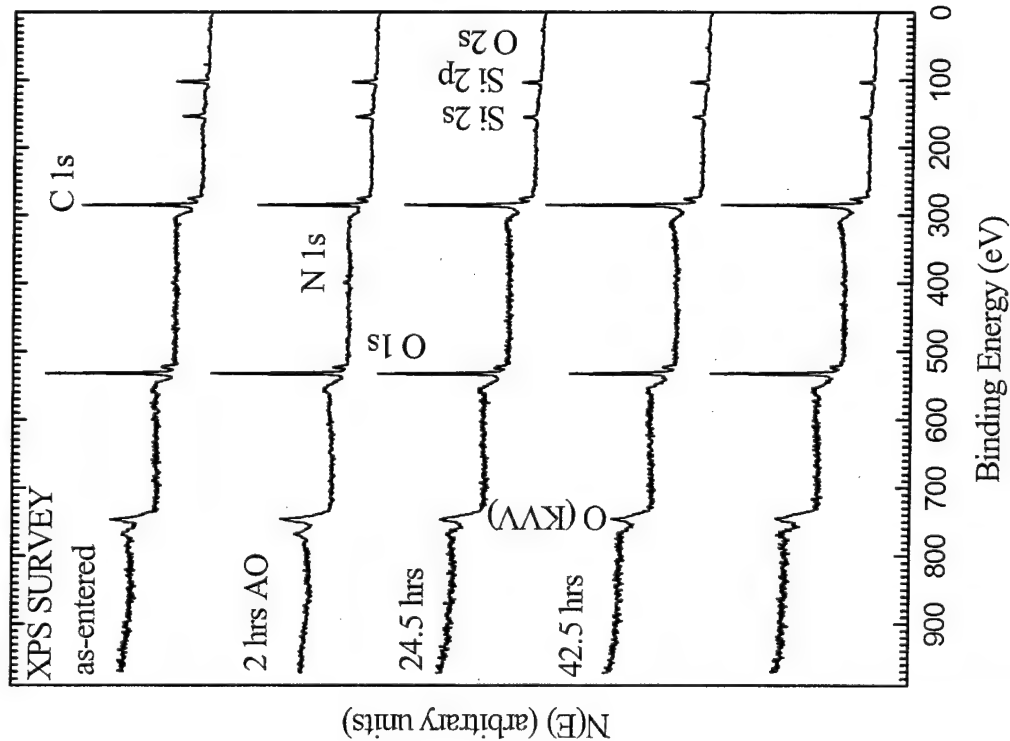
PMDA

OAPS



Octaphenylamino Silsesquioxane Imide Resin

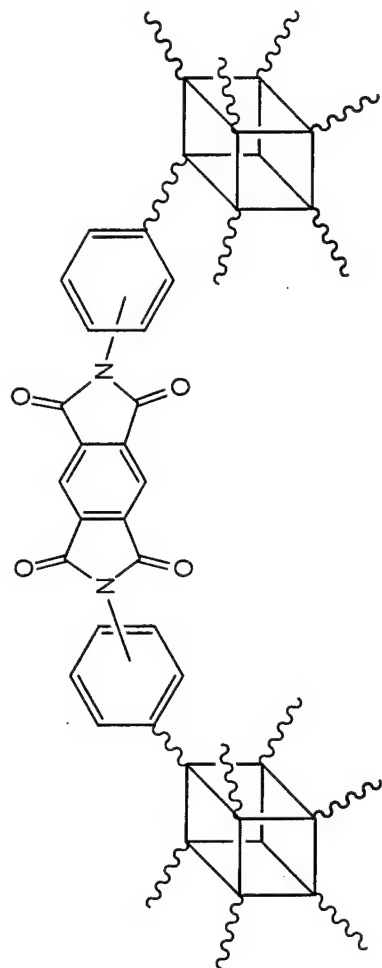
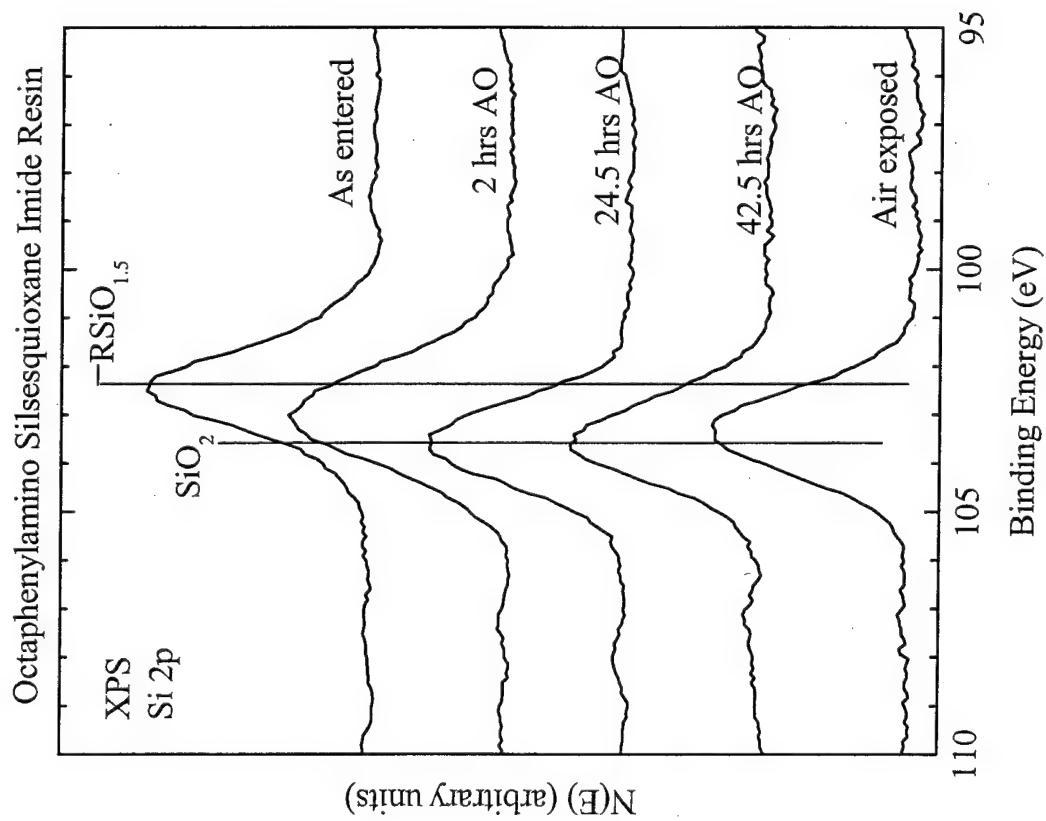
Octaphenylamino Silsesquioxane Imide Resin



Composition, at %

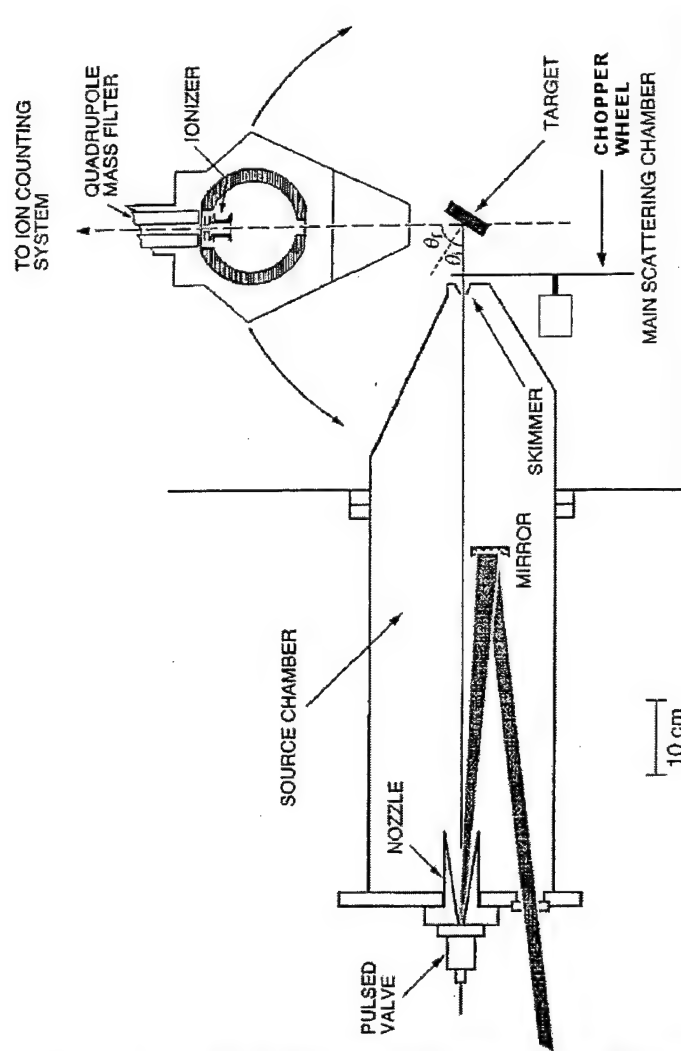
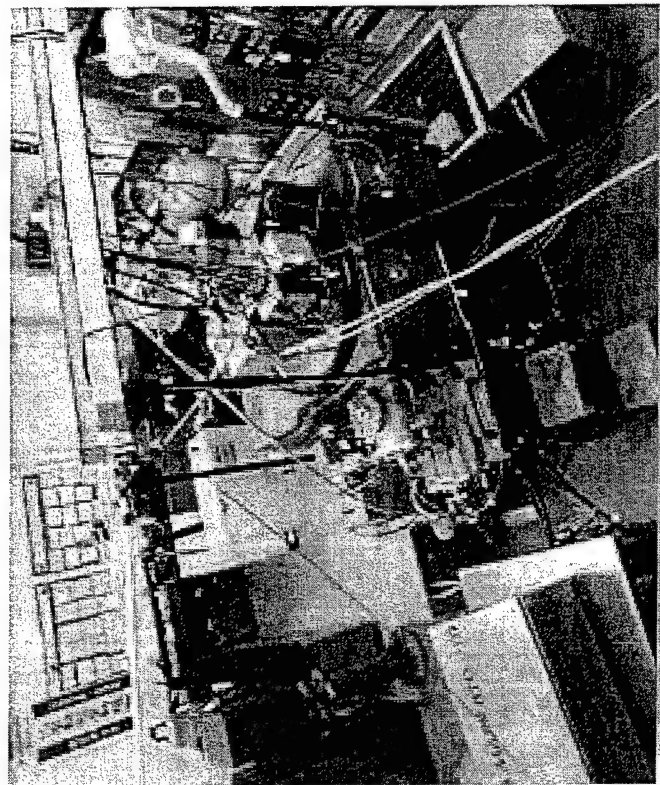
Sample Treatment	O 1s	C 1s	N 1s	Si 2p	O/Si
as entered	18.1	60.5	1.7	19.7	0.9
2hrs	22.8	57.1	2.1	18.0	1.3
24.5hrs	18.7	67.9	1.1	12.3	1.5
42.5hrs	16.2	71.3	2.4	10.1	1.6
Air exposed	19.3	71.5	0.9	8.3	2.3

Octaphenylamino Silsesquioxane Imide Resin



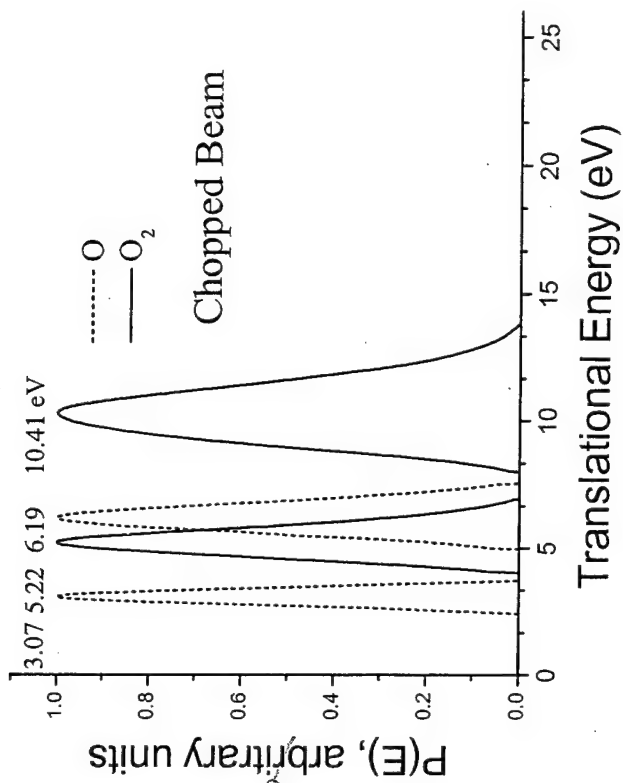
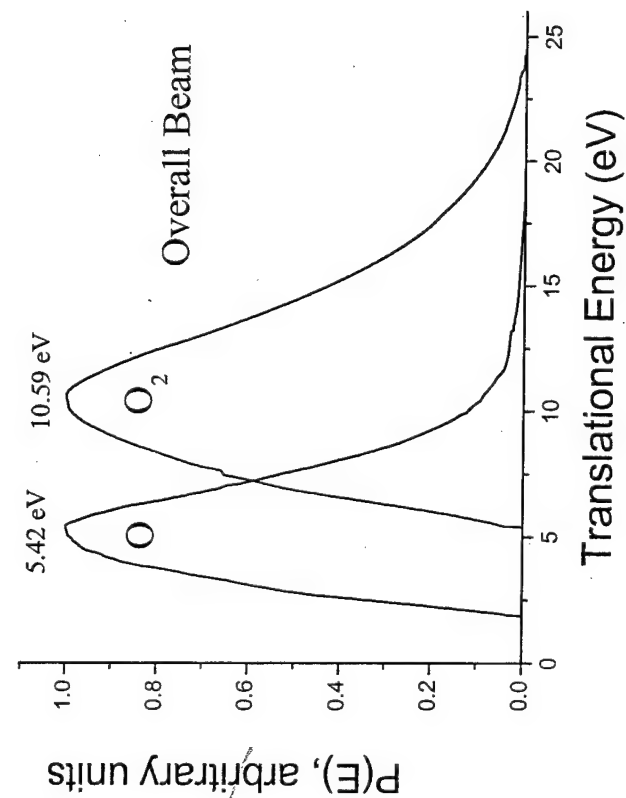


Beam-Surface Scattering/Atomic Oxygen Test Facility



Pulsed CO₂ Laser Atomic Oxygen Generator

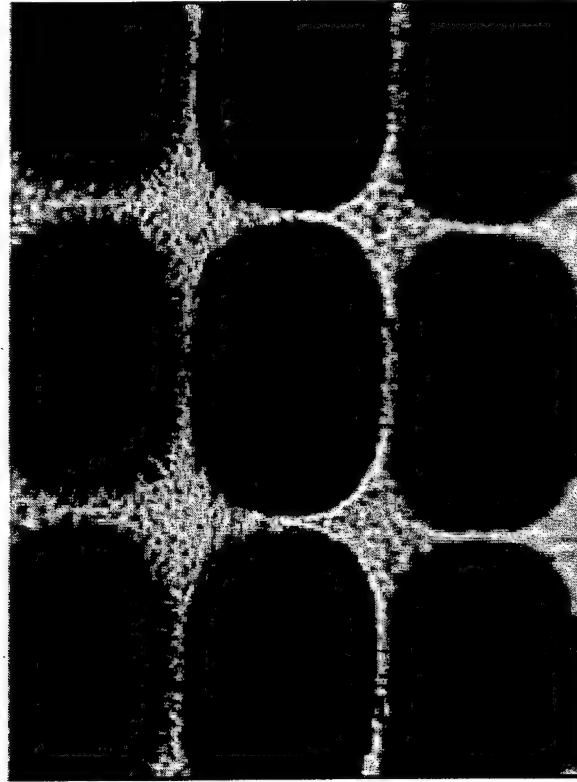
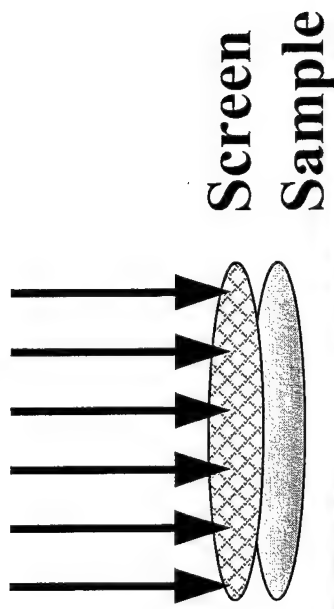
Energy distribution beams produced by the pulsed CO₂ laser AO source



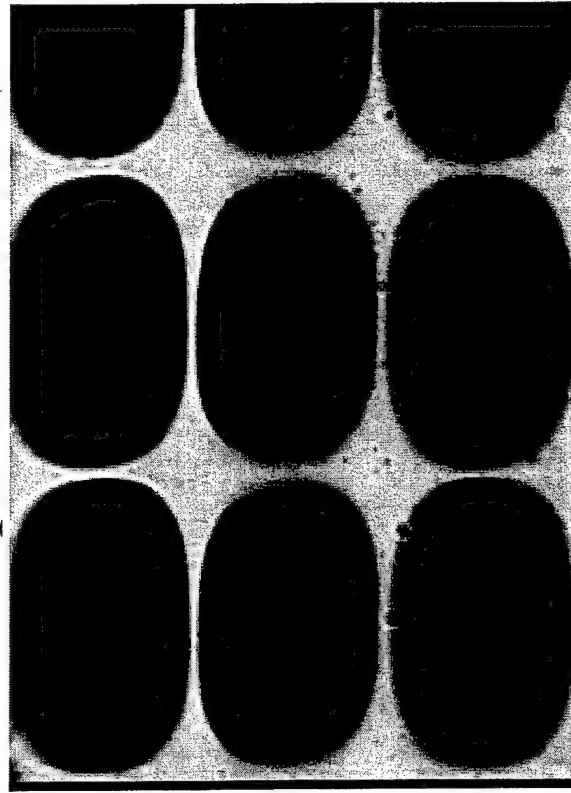


Surface Topographical Analysis/Profilometry

Hyperthermal AO Beam



Kapton H

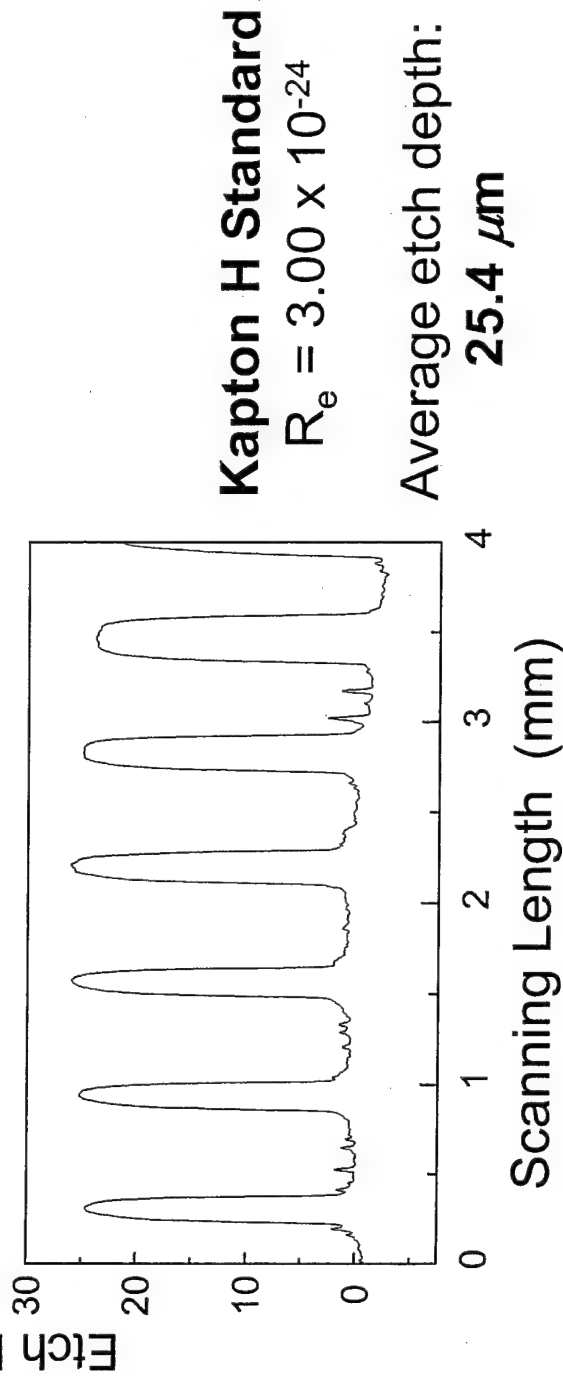
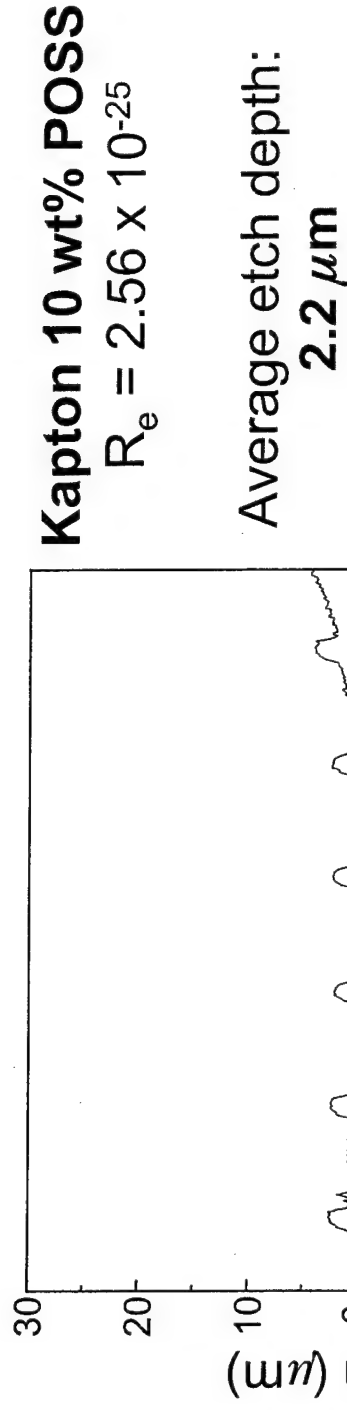


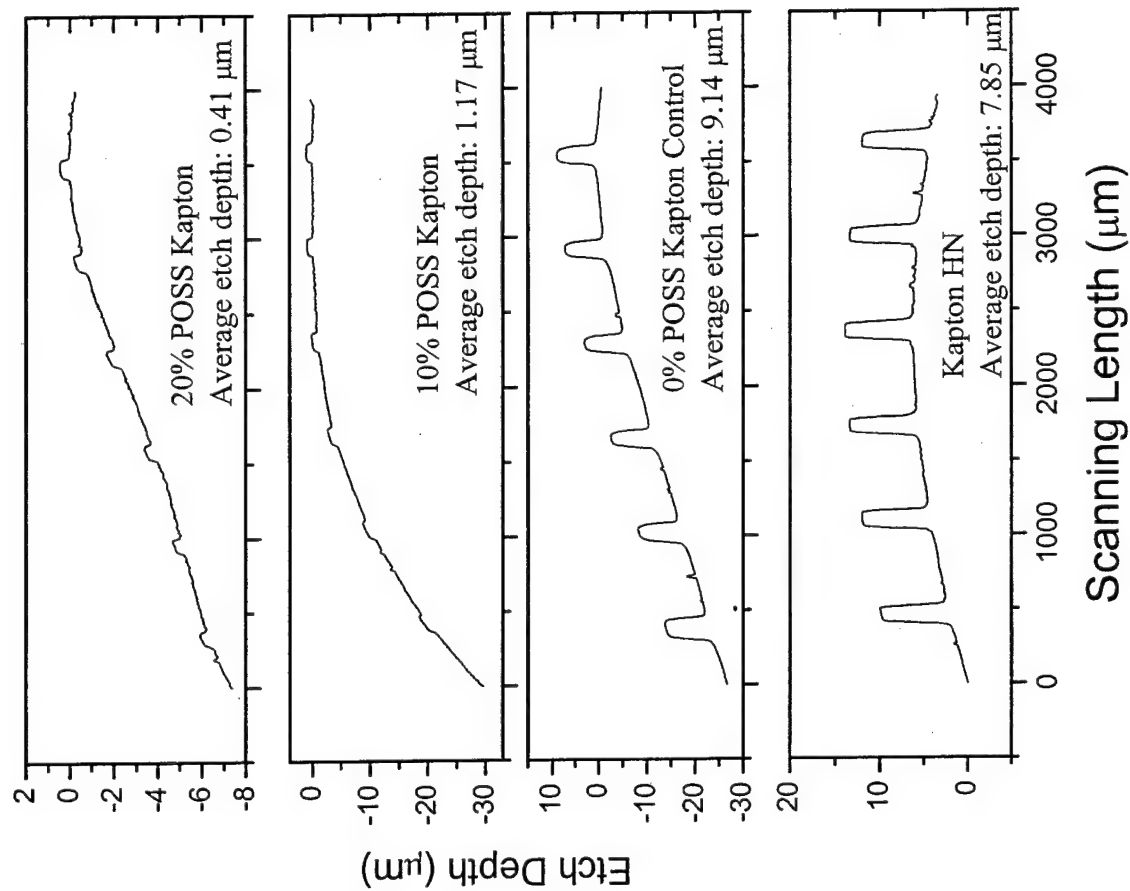
Kapton 10 wt% POSS



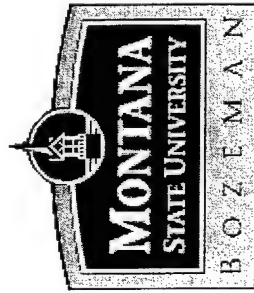
O-Atom Etching Experiment

8.47×10^{20} atoms cm^{-2}





Multiplot of profilometry measurements obtained from Kapton HN and 0, 10 and 20 wt% POSS-Kapton polyimides exposed to a total AO fluence of 2.62×10^{20} atoms/cm².

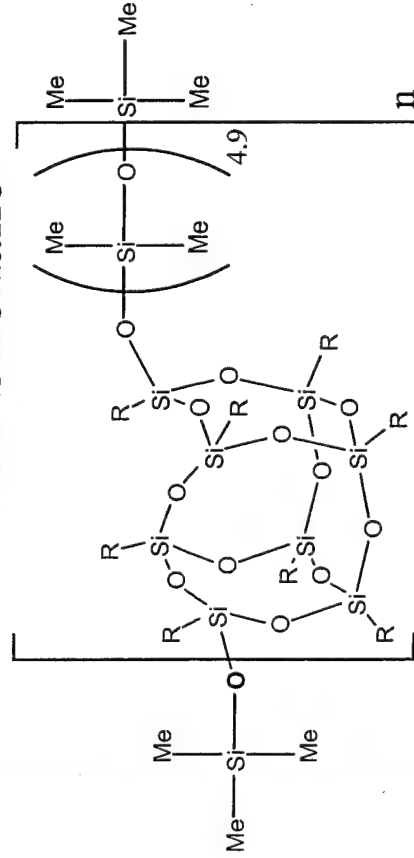


O-Atom Etching Experiment

Total Fluence = 2.62×10^{20} atoms cm^{-2}

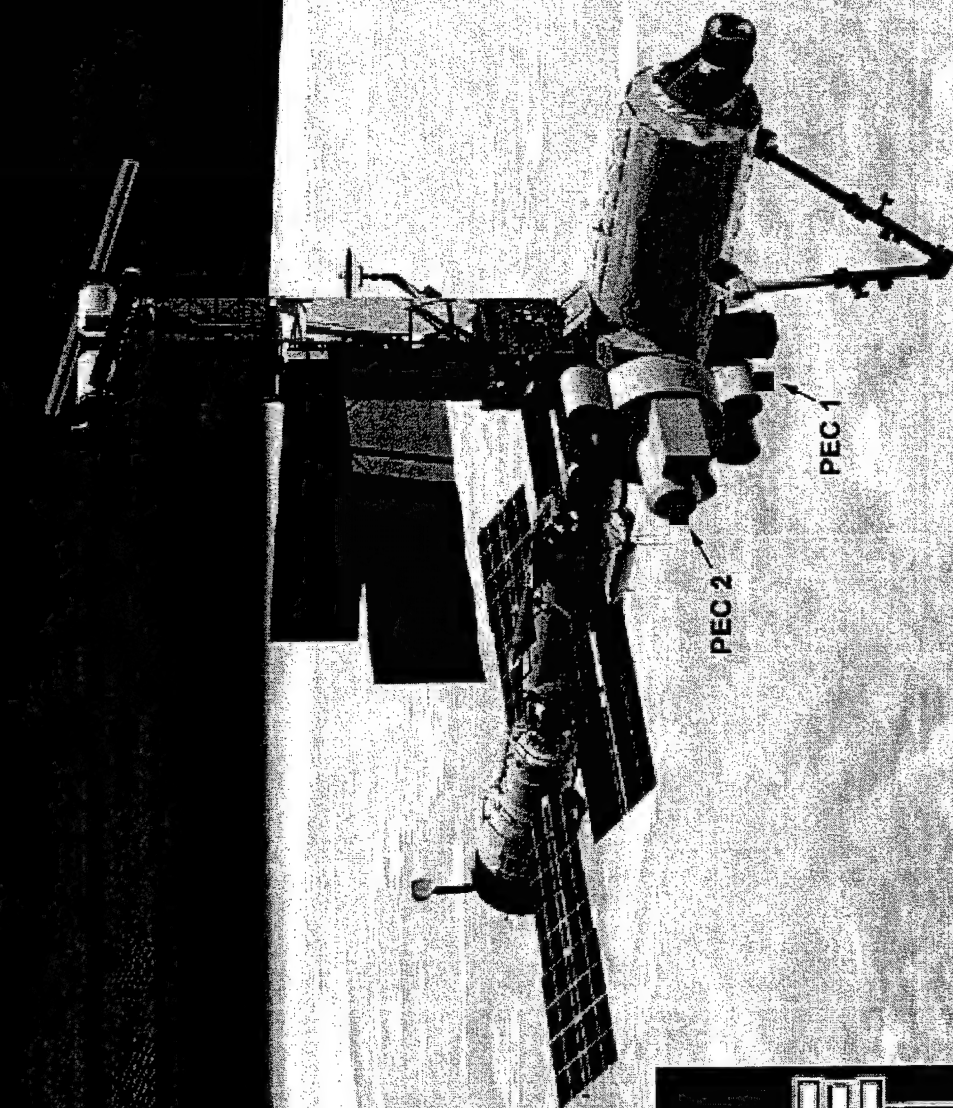
Sample	Kapton H	0% POSS Kapton Control	10% POSS Kapton	20% POSS Kapton	20% POSS- Polyurethane
Avg Etch Depth (microns)	7.85	9.14	1.15	0.41	6.05
Std Deviation	0.05	0.18	0.07	0.07	0.27
Re cm^3/atom	$3.00\text{E-}24$	$3.49\text{E-}24$	$4.39\text{E-}25$	$1.55\text{E-}25$	$2.31\text{E-}24$

POSS Siloxane



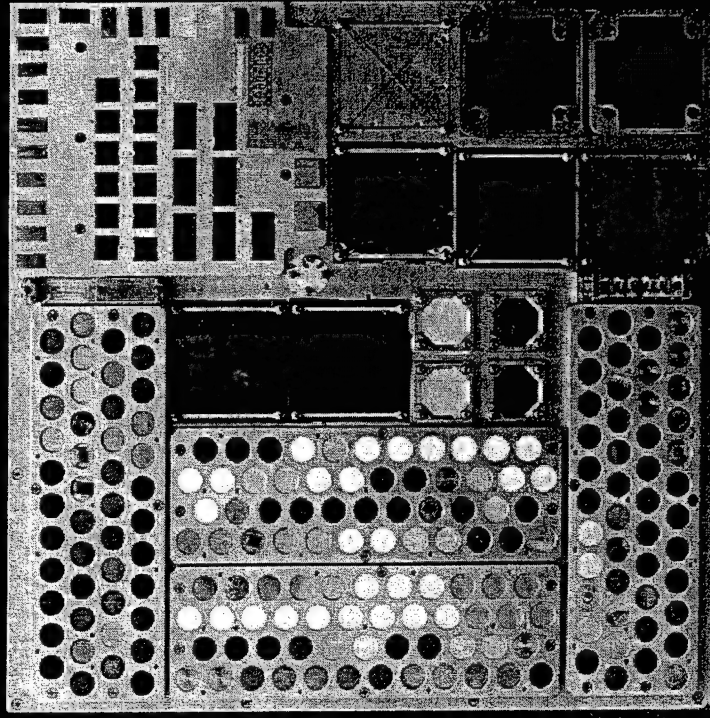
No erosion detected for POSS-Siloxane copolymer

MATERIALS INTERNATIONAL SPACE STATION EXPERIMENT



MATERIALS INTERNATIONAL SPACE STATION EXPERIMENT

1 YEAR AO & SOLAR
TRAY IN PEC 1 - TRAY 1

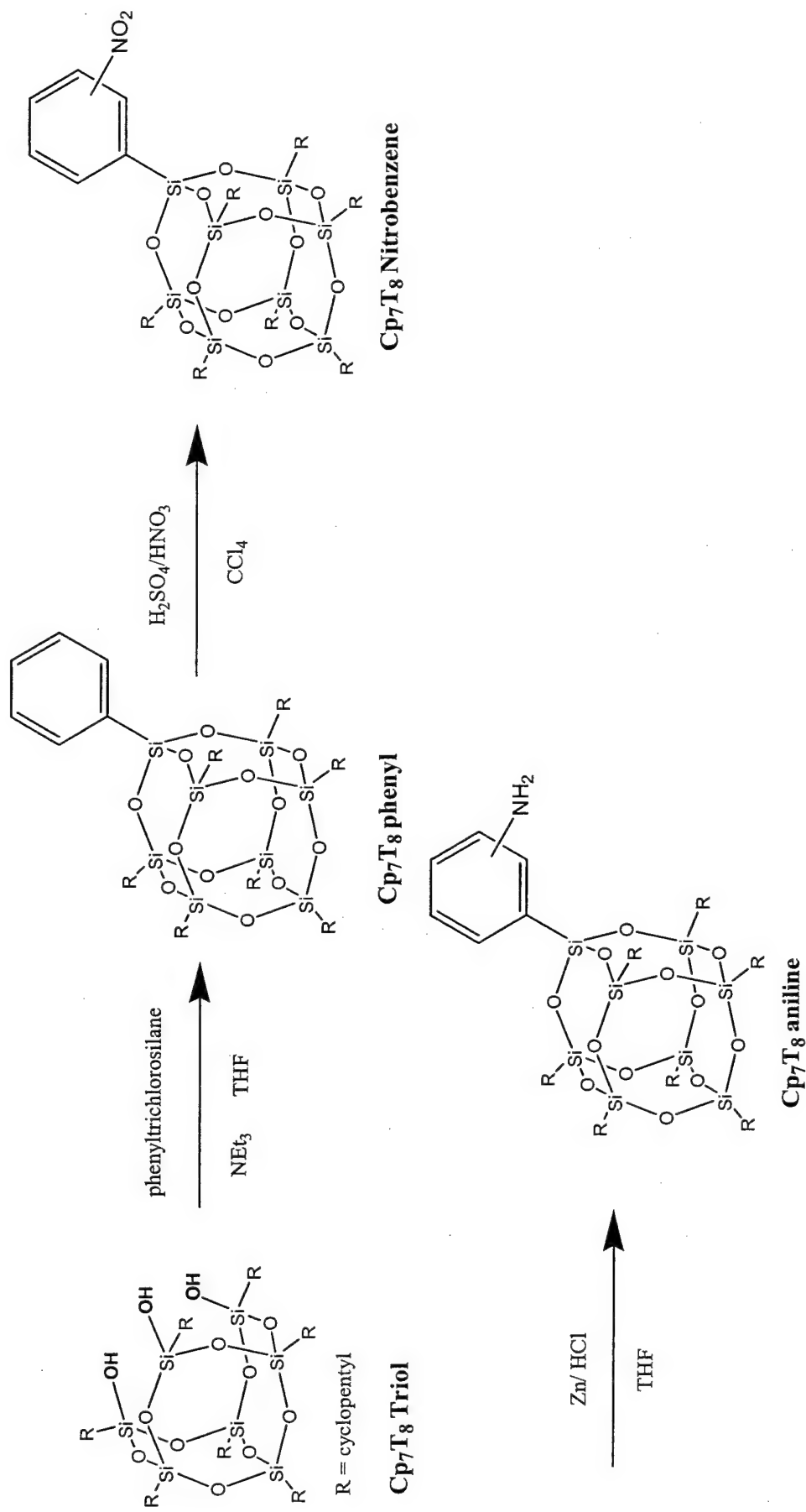


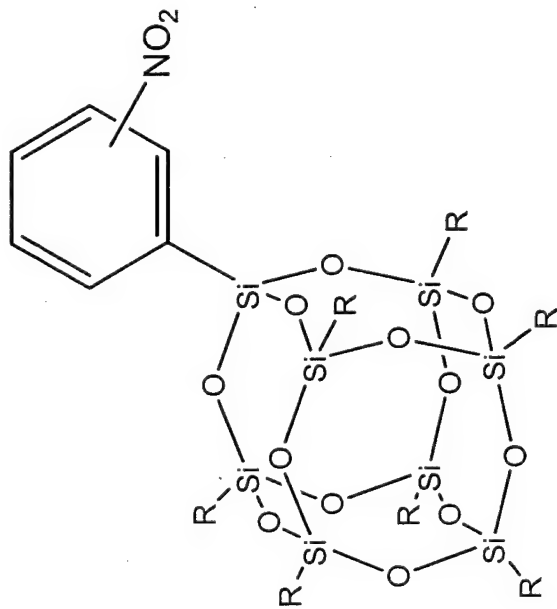
POSS in Space

**POSS-Polymers Fly on
STS 105 Discovery and
are deployed on the
Int'l Space Station
16 August 2001**

Footage courtesy of NASA

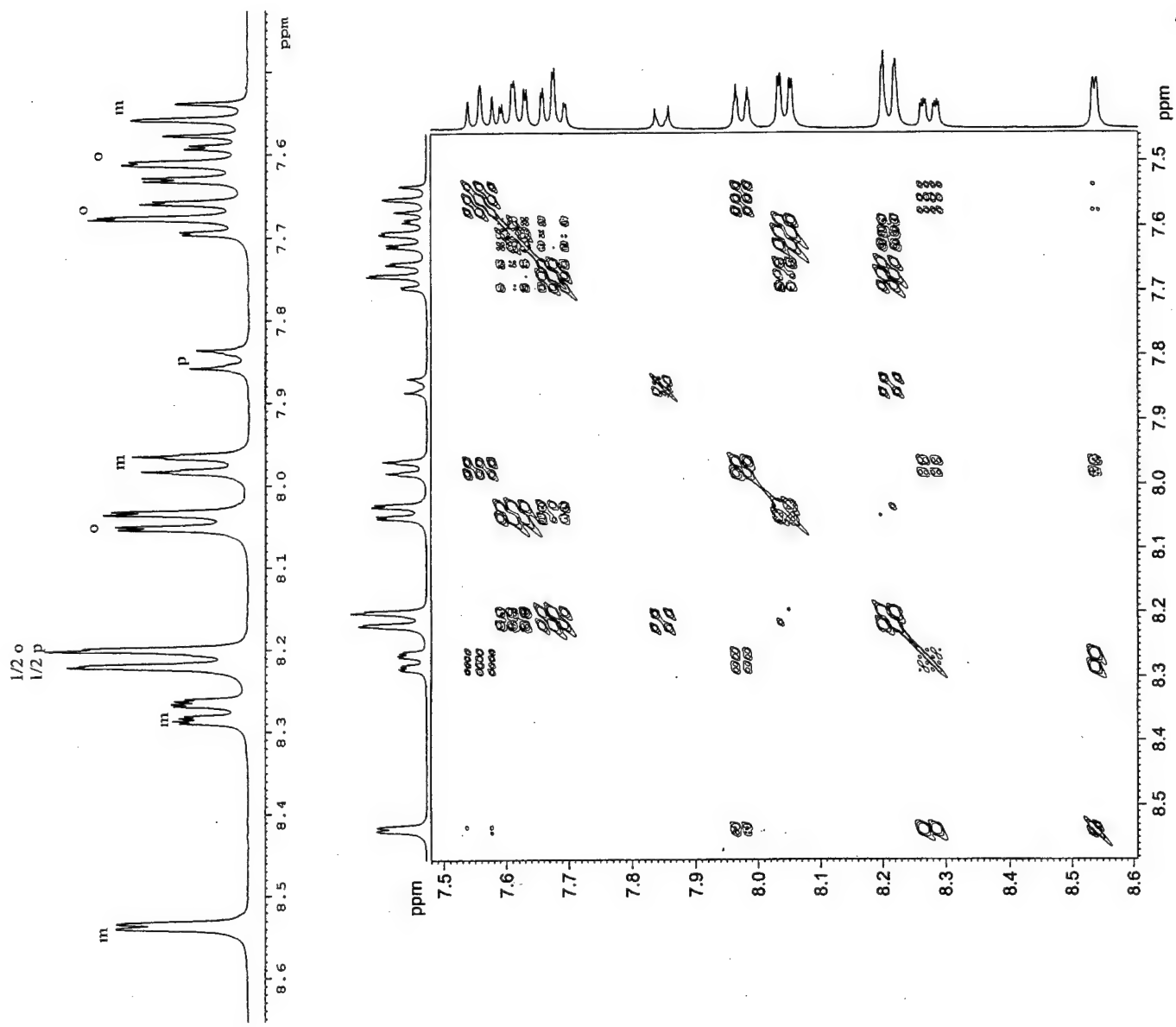
Development of CpPOSS aniline model compound

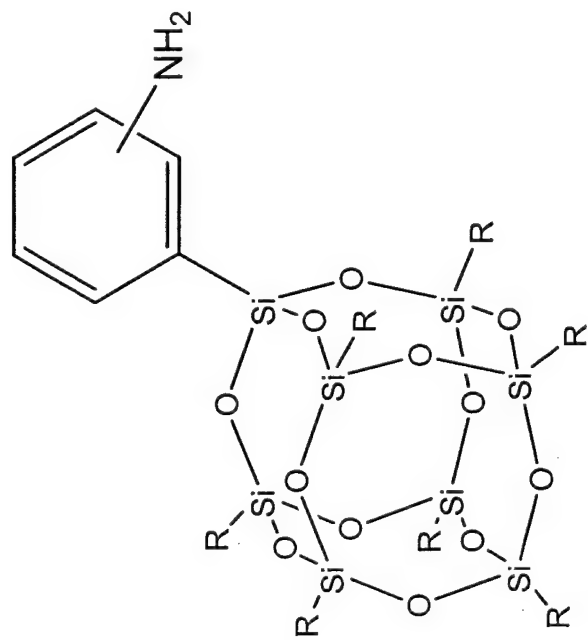




Cp₇T₈ Nitrobenzene

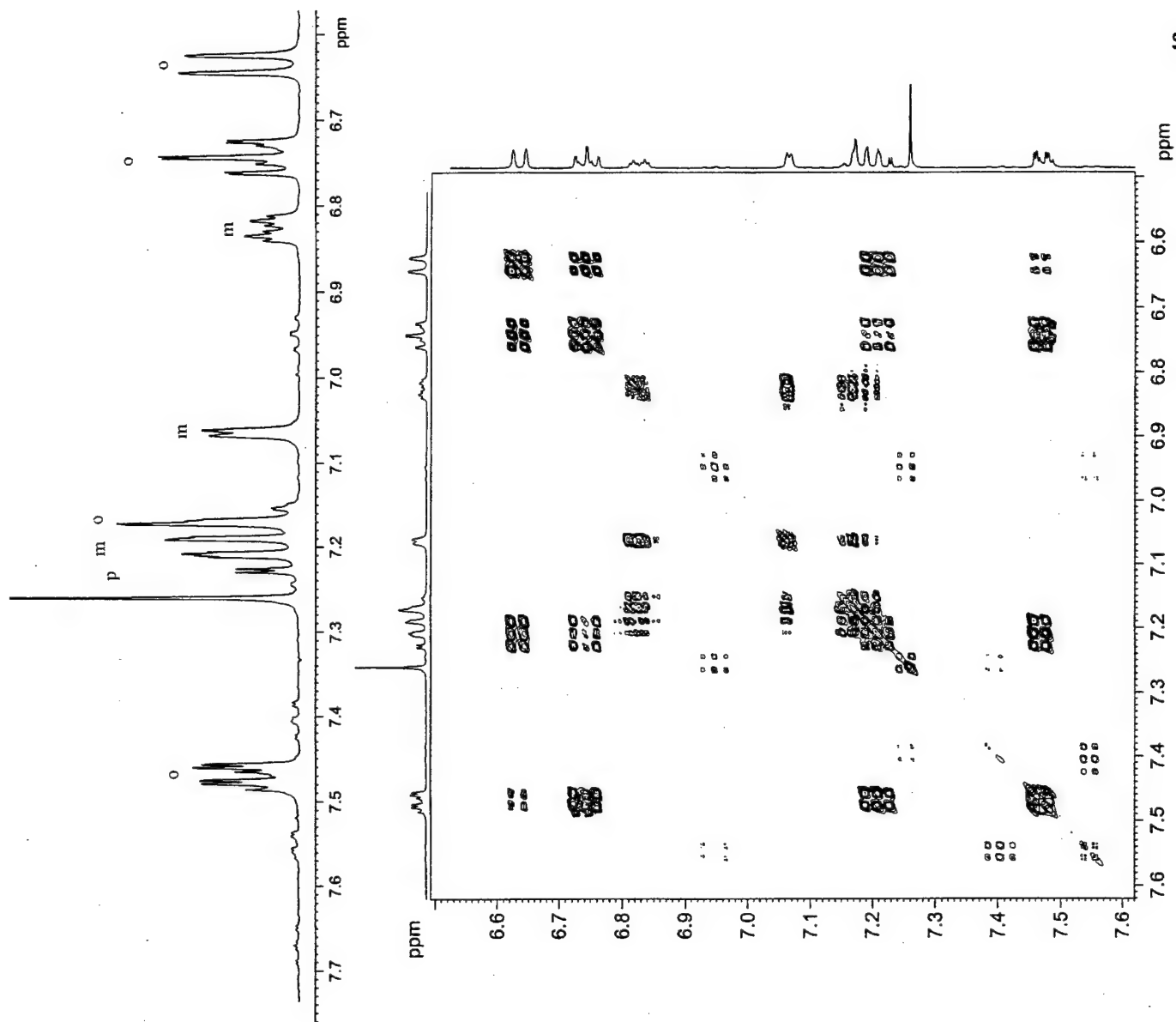
55% ortho
37% meta
8% para

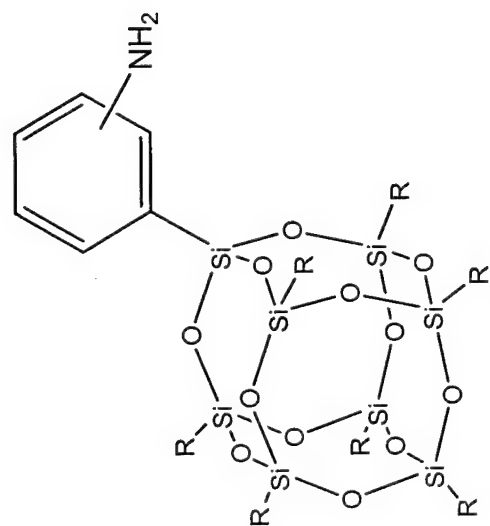




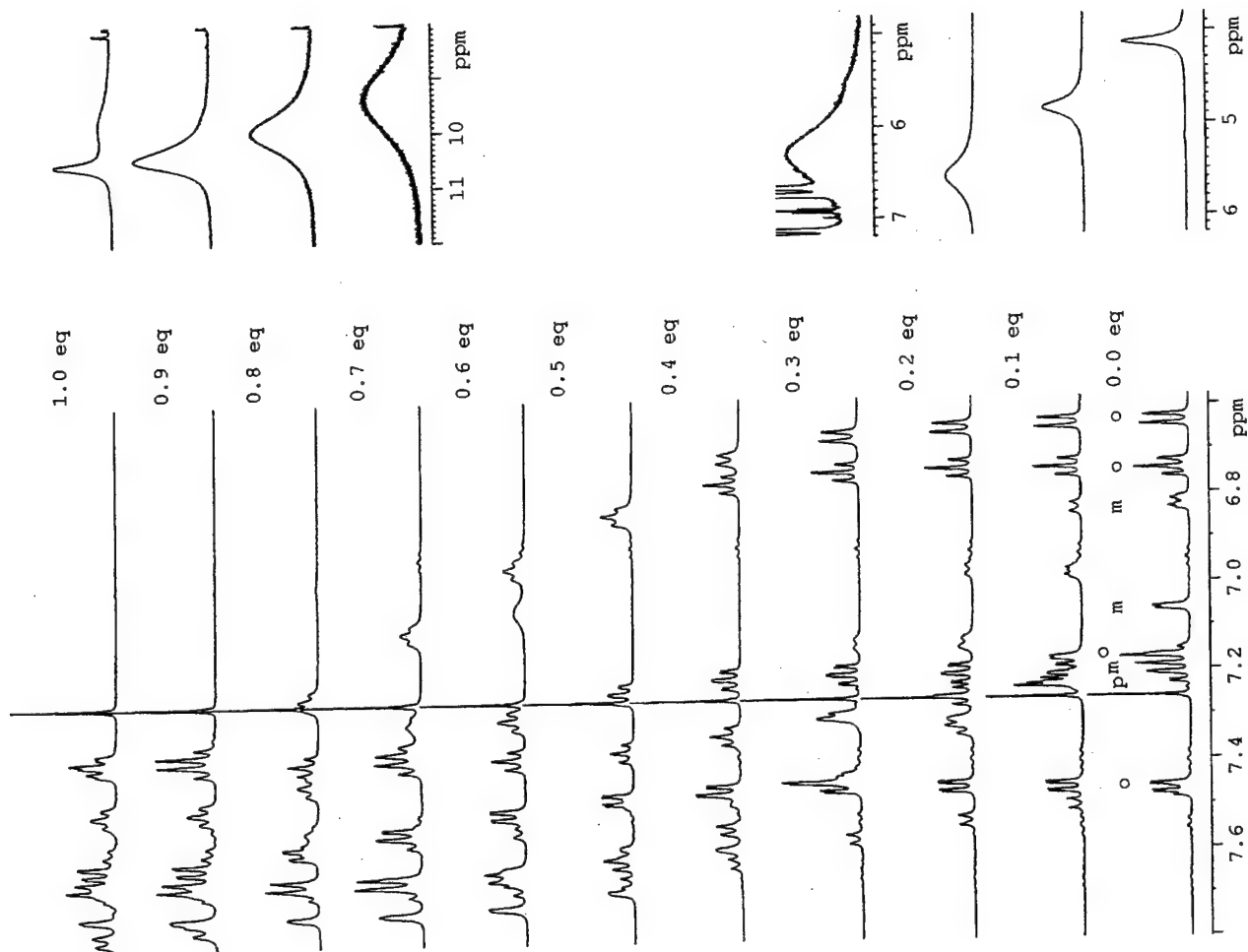
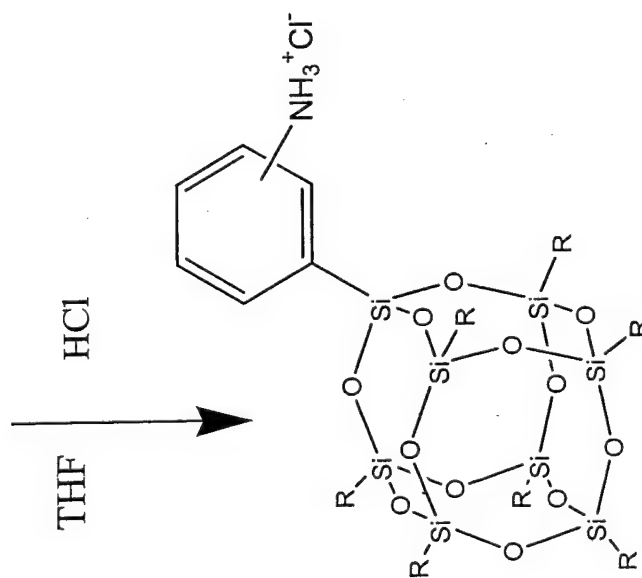
Cp₇T₈ aniline

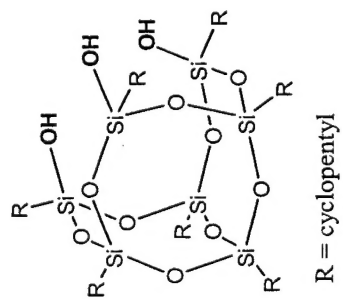
57% ortho
38 % meta
5% para





Cp₇T₈ aniline

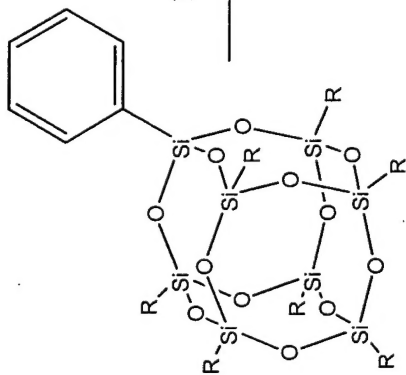




Cp₇T₈ Triol

phenyltrichlorosilane

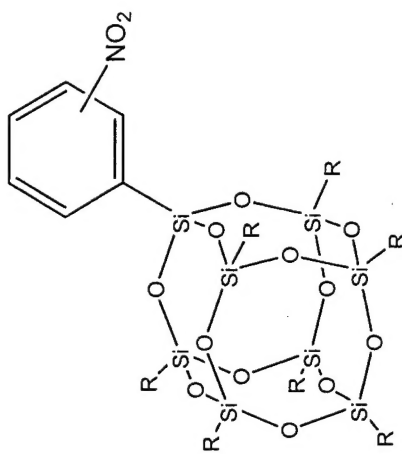
NEt₃ THF



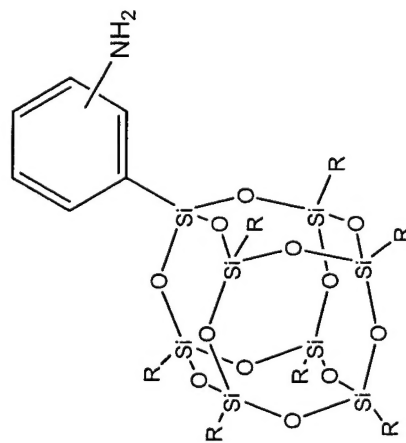
Cp₇T₈ phenyl

H₂SO₄/HNO₃

CCl₄



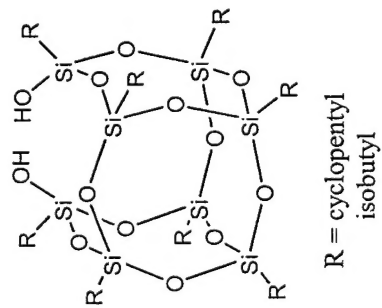
Cp₇T₈ Nitrobenzene



Cp₇T₈ aniline

Zn/HCl

THF



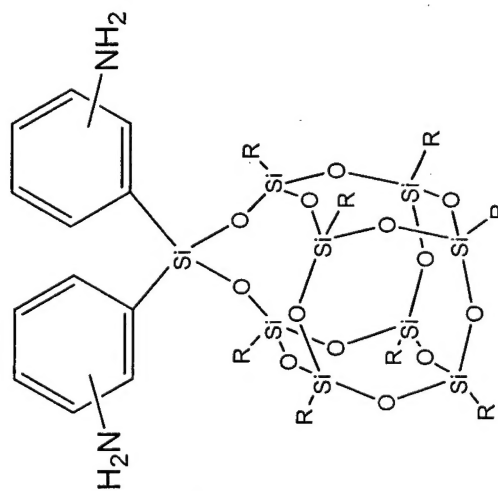
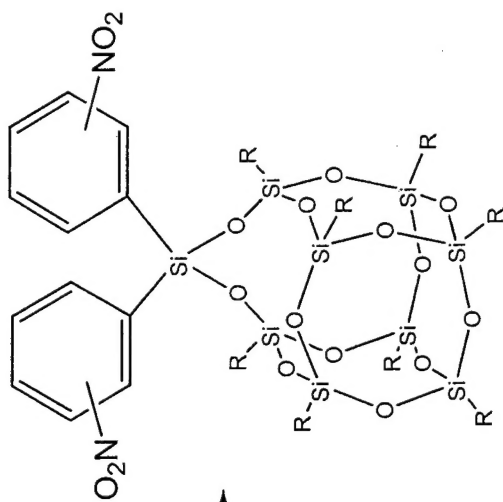
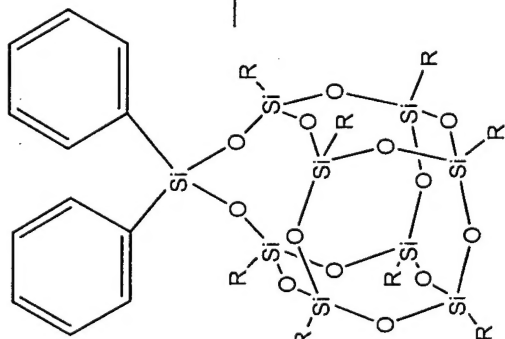
POSS endo diol

diphenyldichlorosilane

NEt₃ THF

H₂SO₄/HNO₃

CCl₄

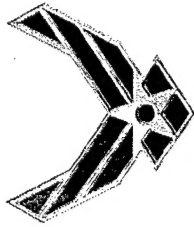


Zn/HCl

THF

Cp₈ or Ibug T₈D₁ dianiline

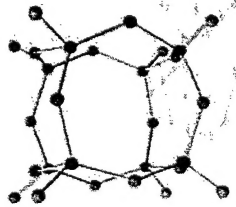
Cp₈ or Ibug T₈D₁ dinitrobenzene



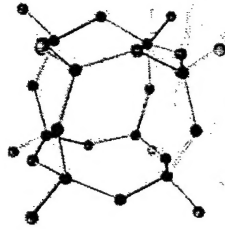
Future Work



- Synthesis of other POSS-analine monomer. AFRL & HP
- Continue AO studies on other POSS-Polymer systems at UF
 - VUV Radiation with and without AO.
 - In-Situ Characterization XPS FTIR
 - Exposure to Different Gases
 - Sputtering Effects using FABS
 - Temperature Effects
- AO Etching and Profilometry Experiments at MSU
- VUV, Proton and Electron Radiation at Aerospace



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AFRL